

Electron Microscopy in Catalysis

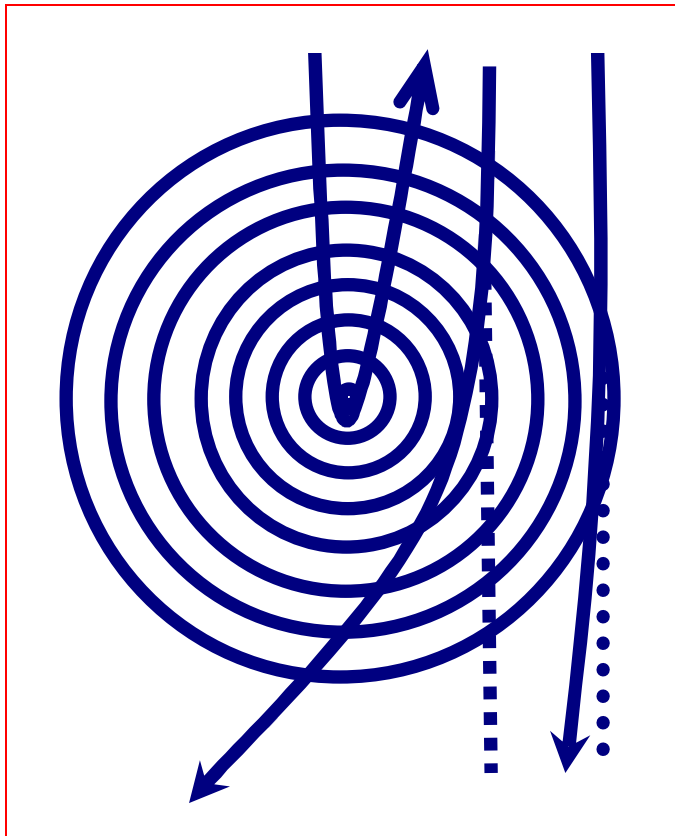
Di Wang



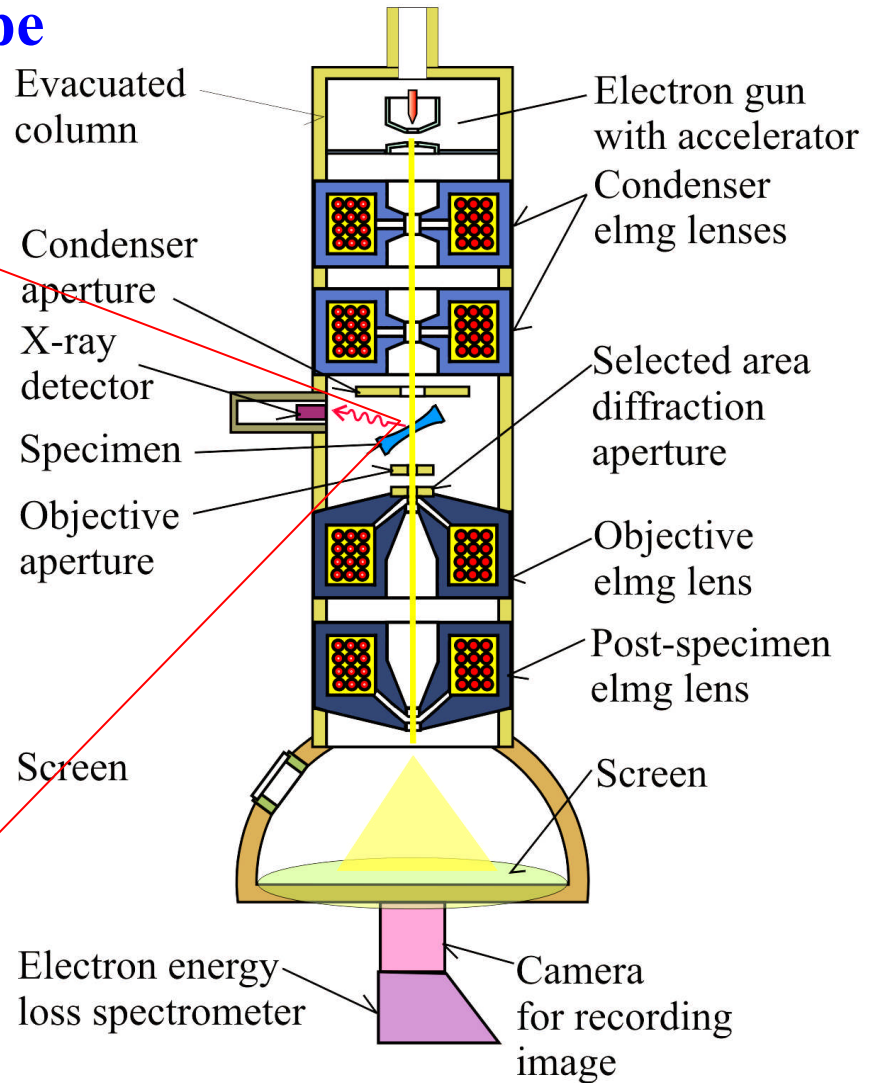


Transmission electron microscope

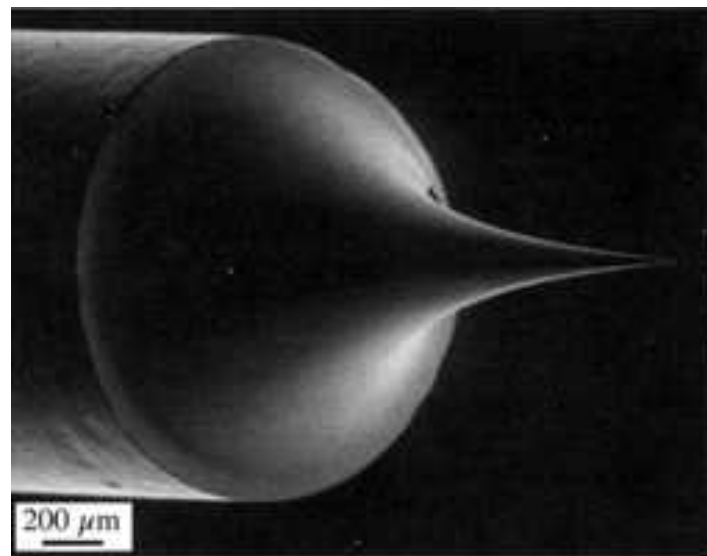
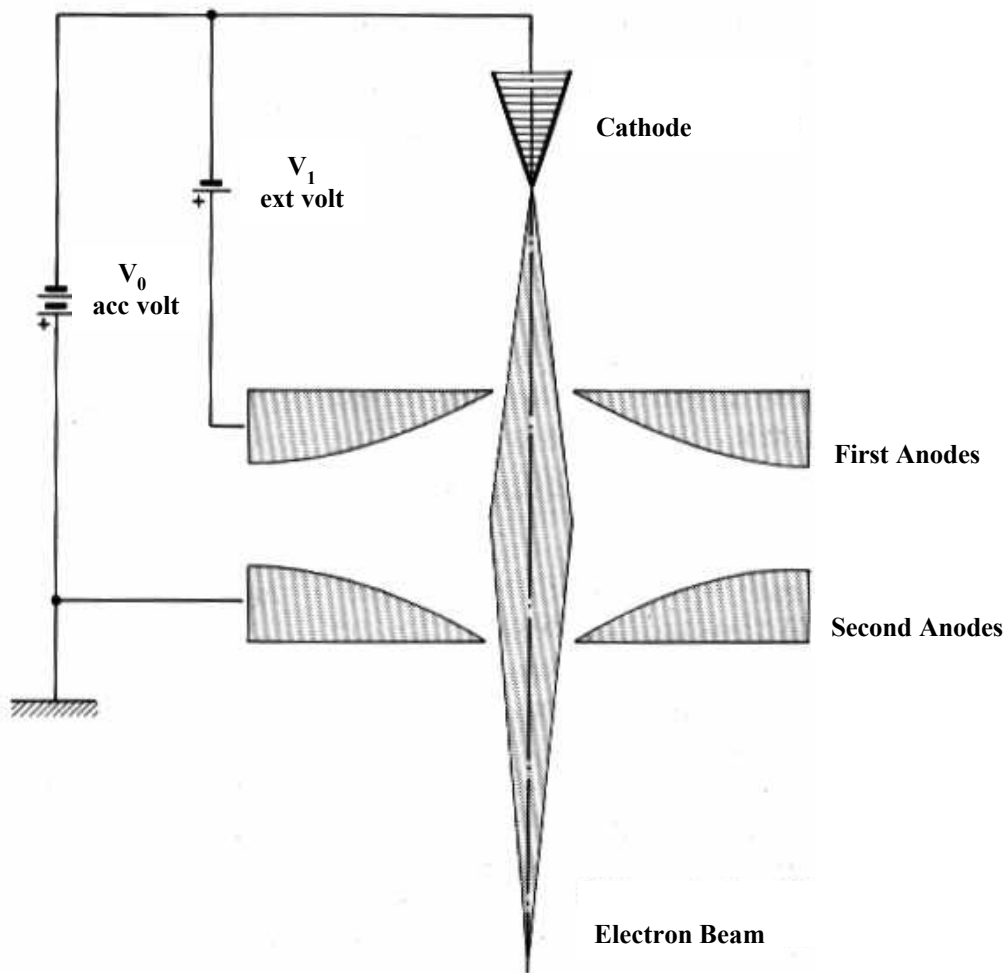
Interaction of electron with your samples



Electron scattering

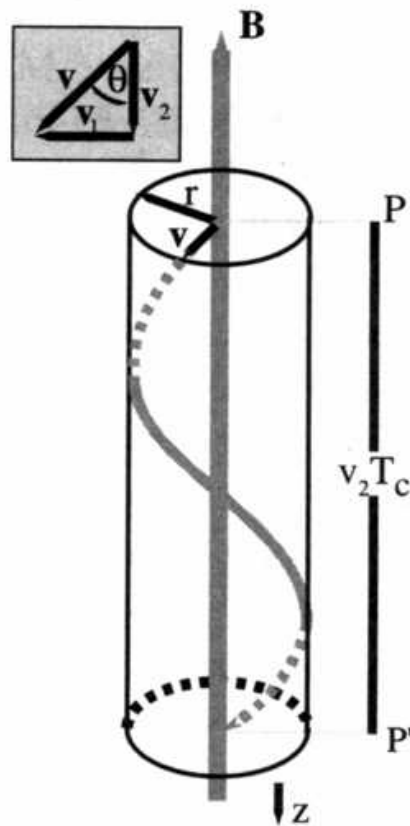
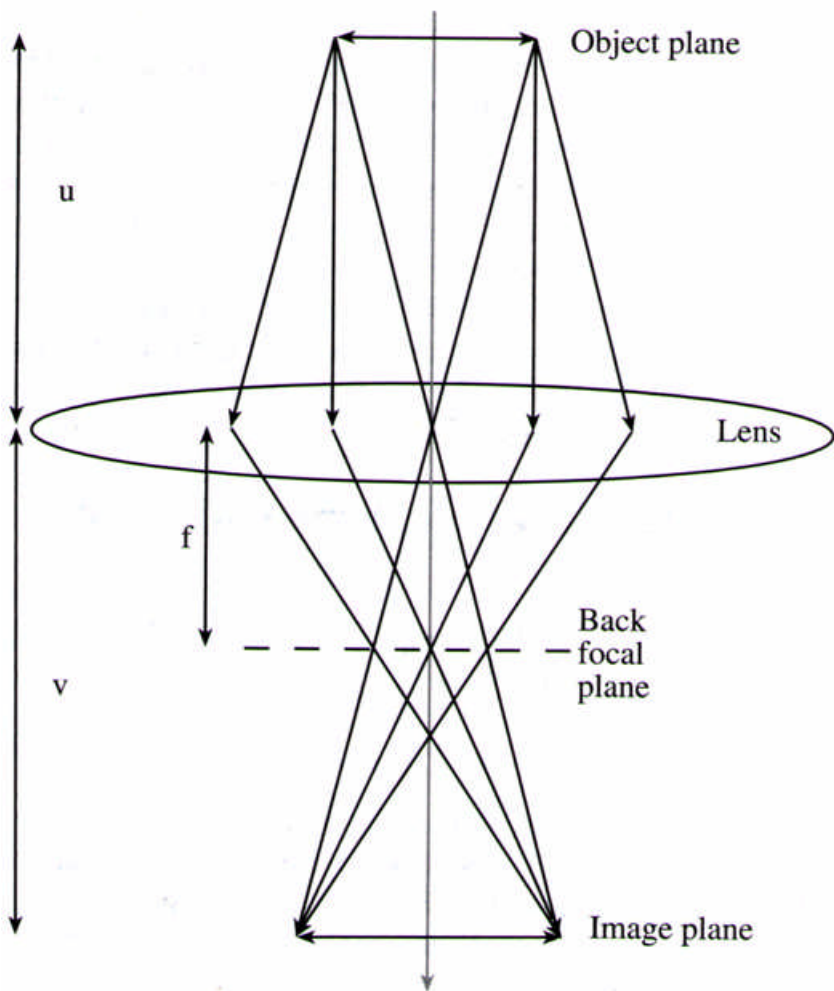


Field emission gun

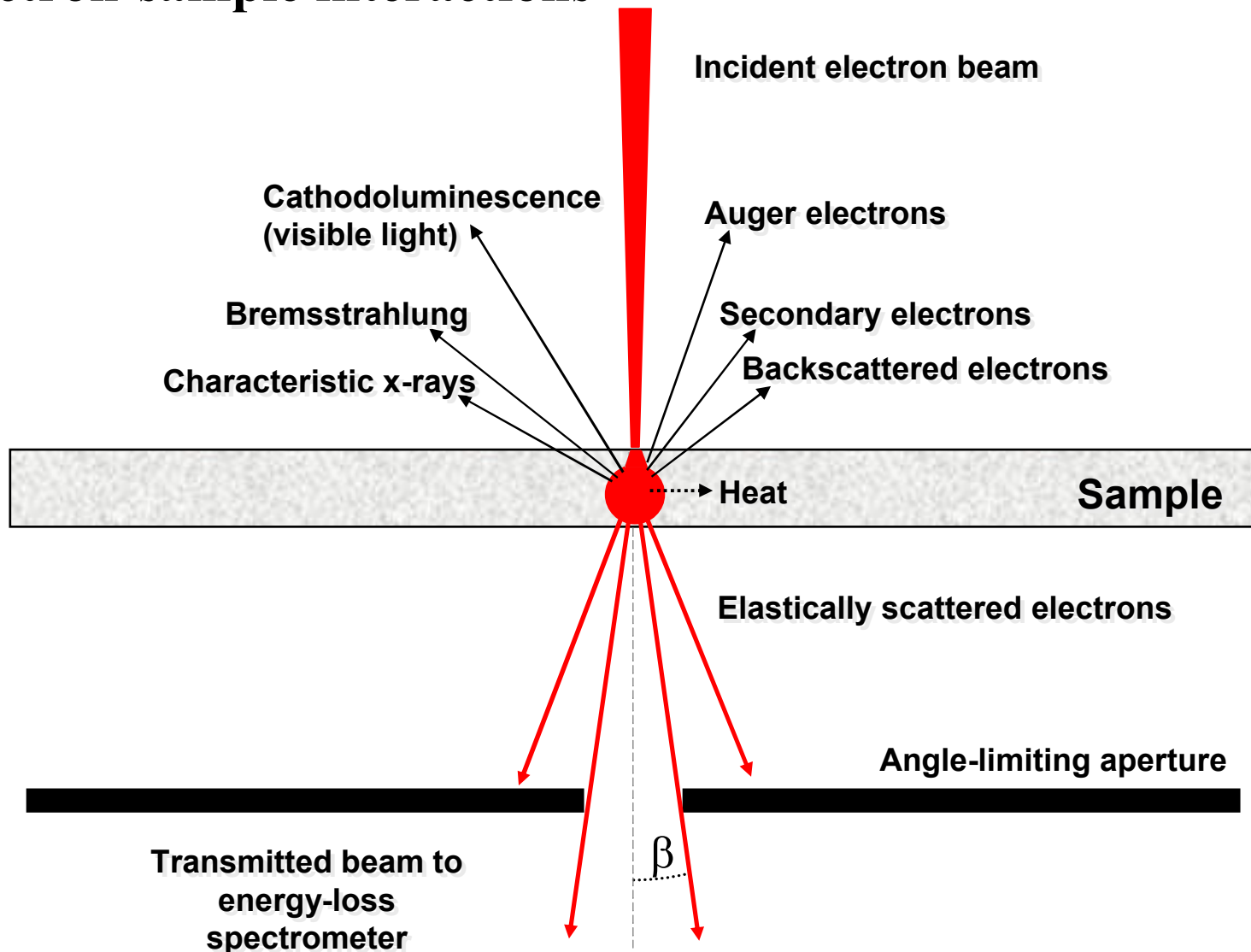


An FEG tip, showing the extraordinarily fine W needle

Lens



Electron-sample interactions



What can TEM do?

TEM

Morphology

Bright field and dark field imaging

Defects, Phases

High-resolution imaging

Defects, Interfaces, Surfaces

Electron diffraction

Structure

Convergent-beam diffraction

Symmetry, Strain
Lattice parameter

Energy-dispersive X-ray spectroscopy (EDX)

Element analysis

Electron-energy loss spectroscopy (EELS)

Electronic structures

Energy-filtered TEM (EFTEM)

Imaging the distribution of
elements and even chemical states

SEM

Morphology, surfaces

STEM

Morphology, Z-contrast

Image and diffraction mode

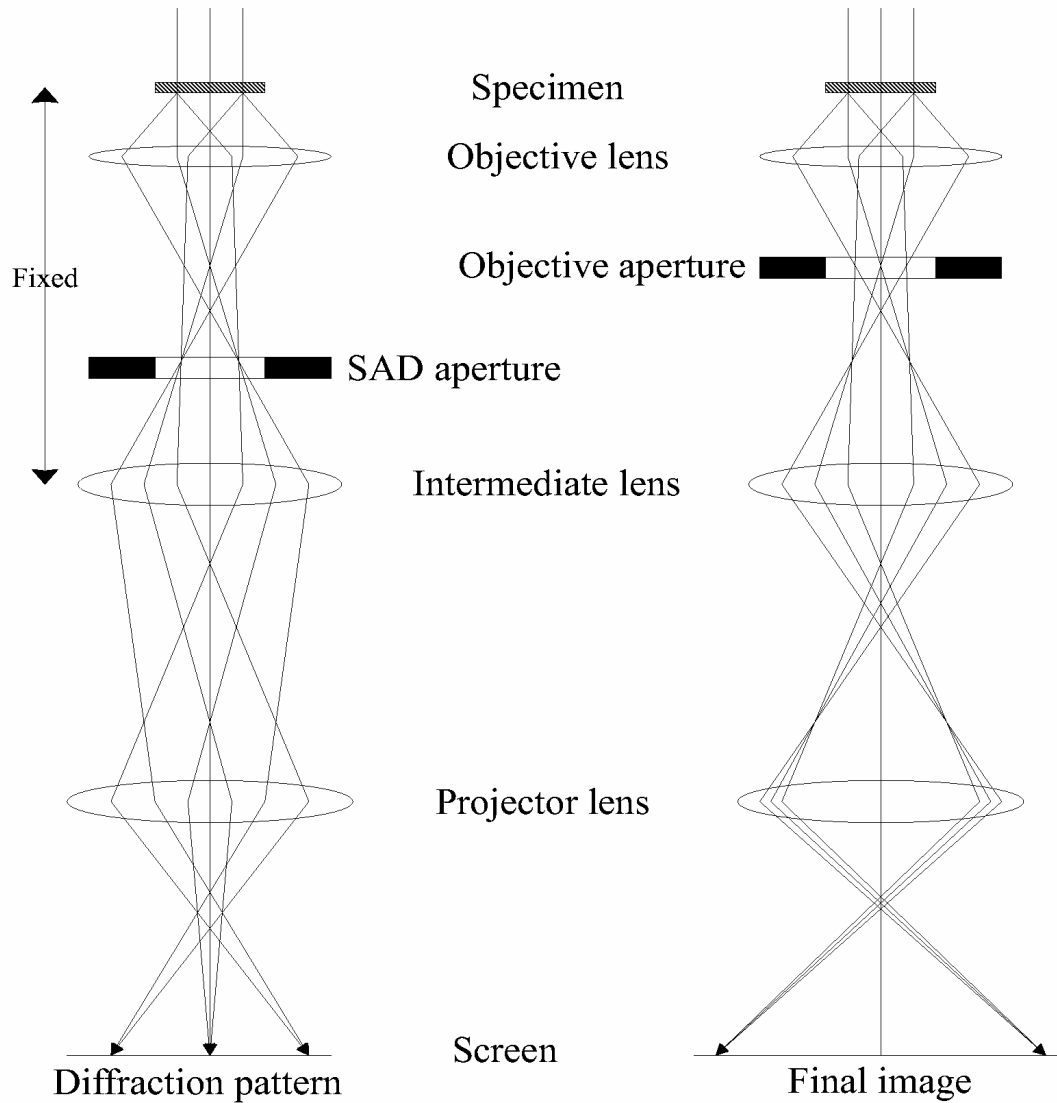


Image contrast in TEM

I. Mass-thickness contrast

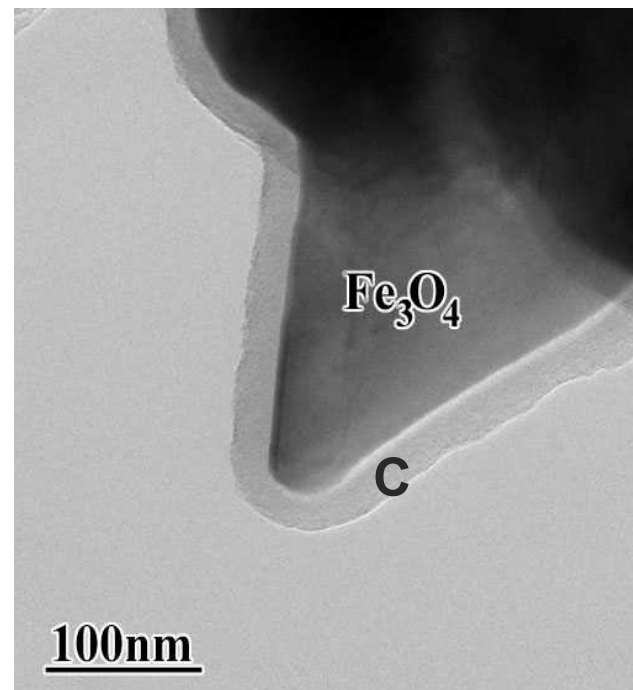
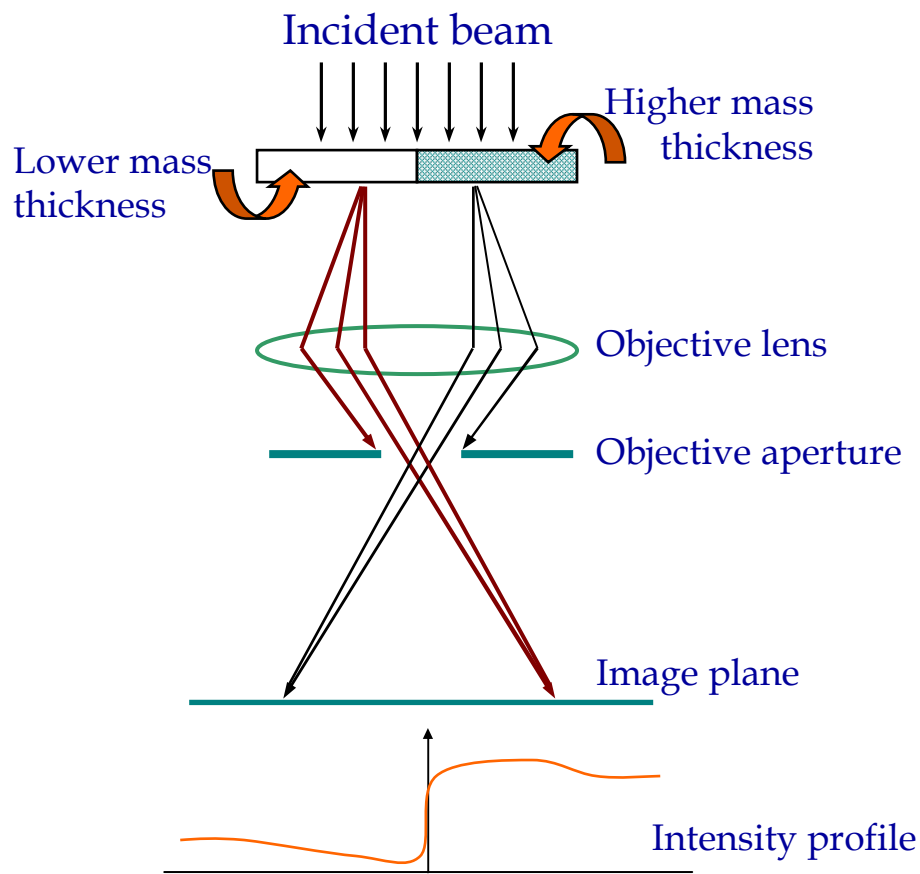


Image contrast in TEM

II. Diffraction contrast

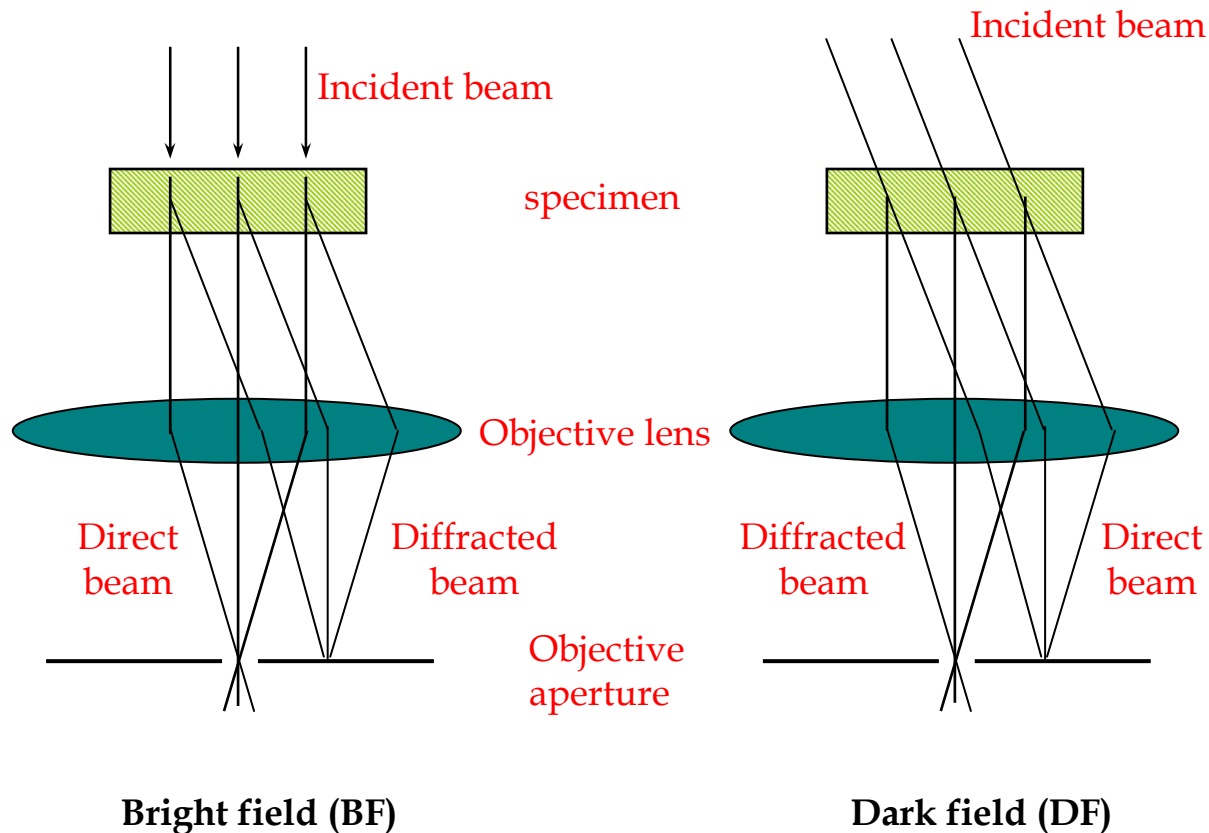
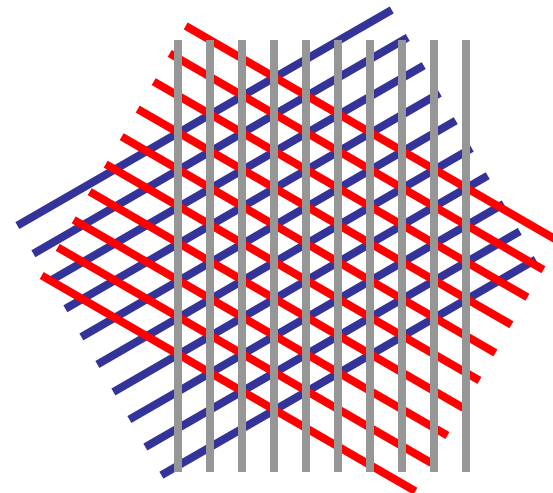
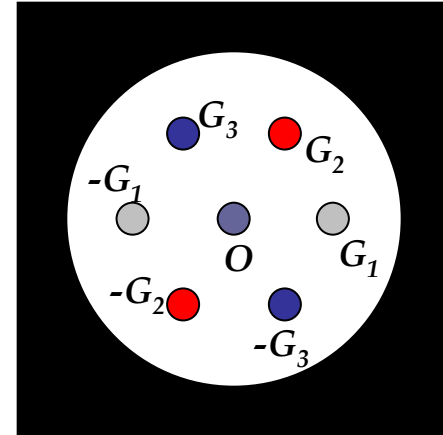
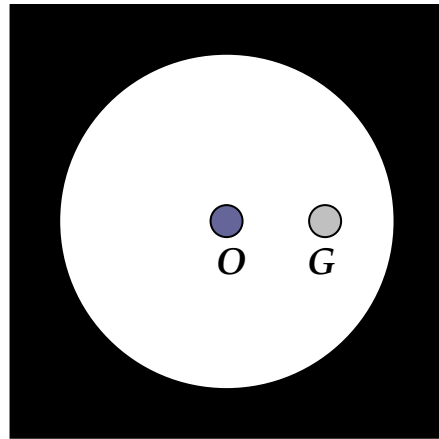
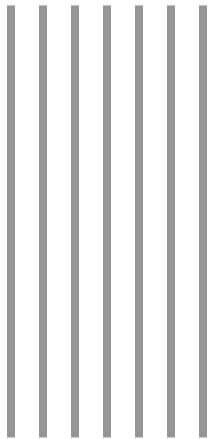
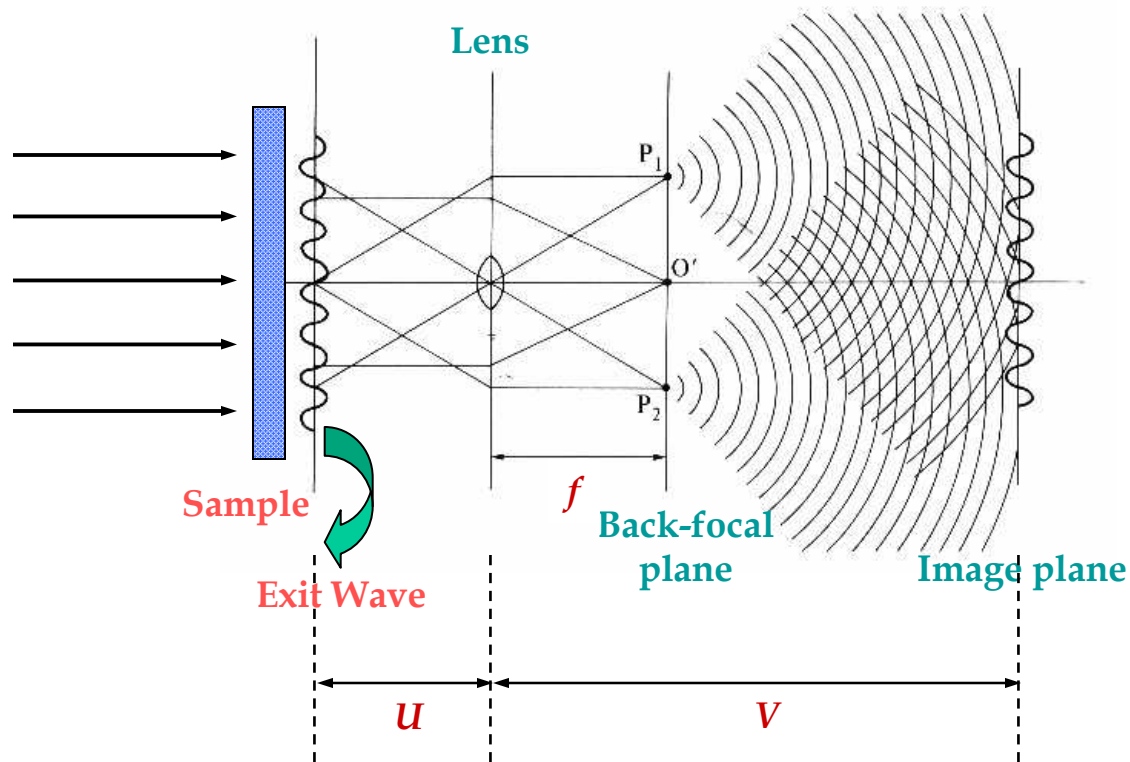


Image contrast in TEM

III. Lattice fringes in pictures

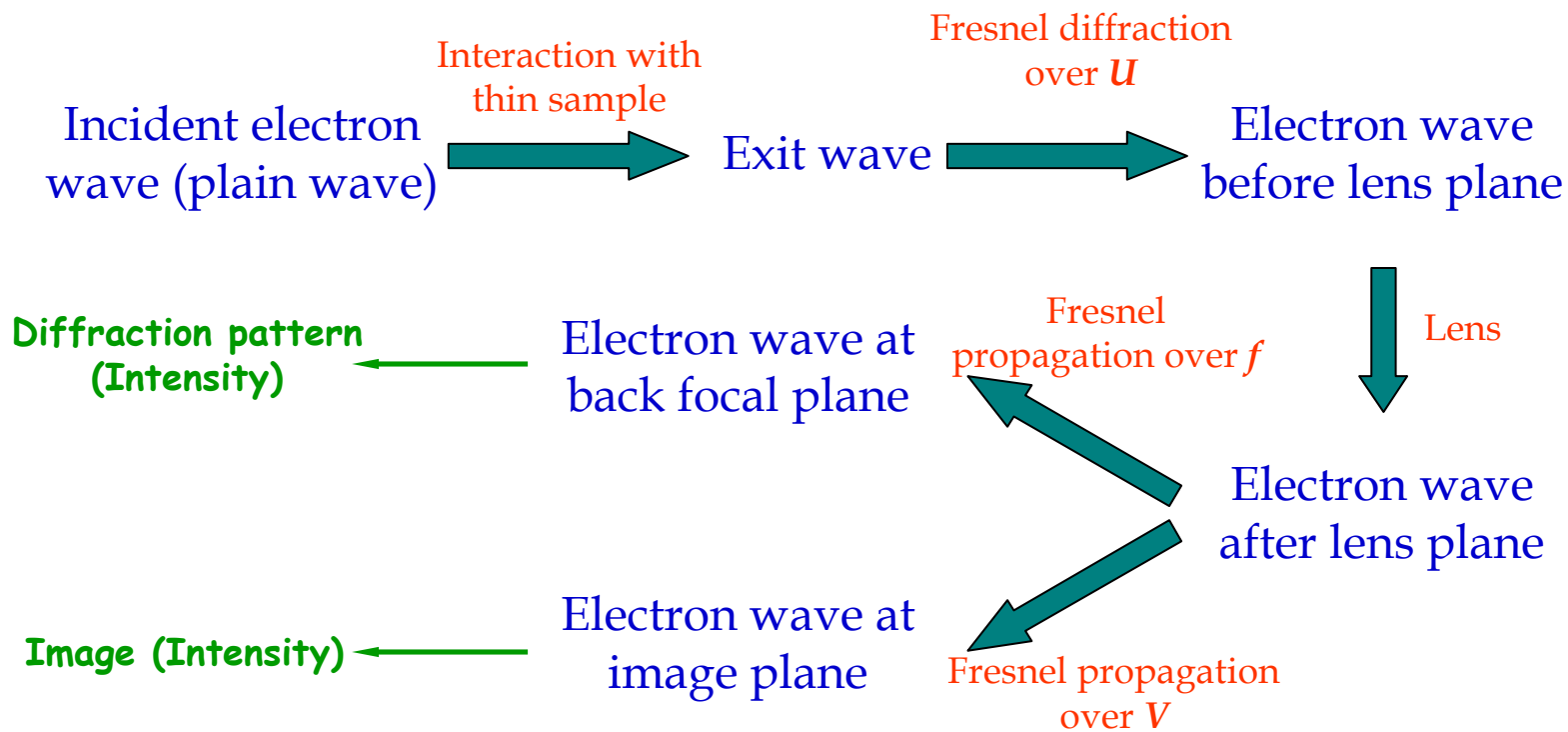


High-resolution imaging



Abbe Interpretation of imaging

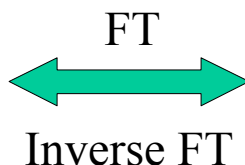
Abbe Interpretation of imaging



Fourier transform (FT)



Real space



Reciprocal space

$$\mathbf{a}^* = \frac{\mathbf{b} \times \mathbf{c}}{V}, \mathbf{b}^* = \frac{\mathbf{c} \times \mathbf{a}}{V}, \mathbf{c}^* = \frac{\mathbf{a} \times \mathbf{b}}{V}$$

For cubic, tetragonal and orthorhombic structure,

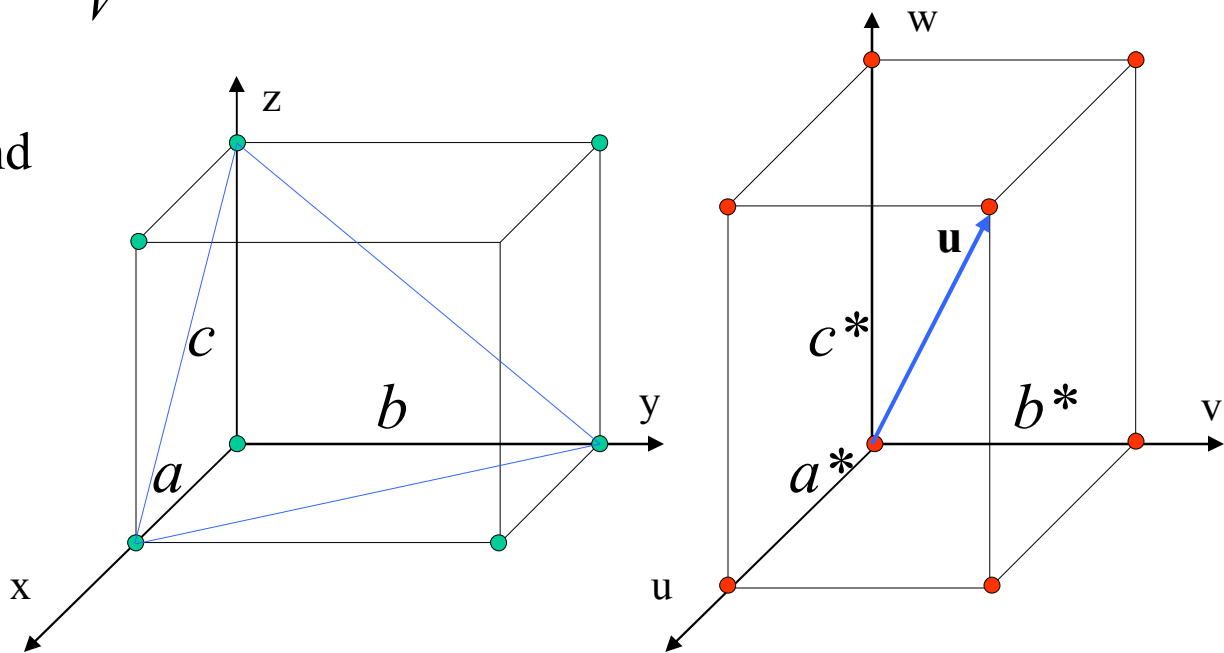
$$\mathbf{a}^* = 1/a, \parallel \mathbf{a}$$

$$\mathbf{b}^* = 1/b, \parallel \mathbf{b}$$

$$\mathbf{c}^* = 1/c, \parallel \mathbf{c}$$

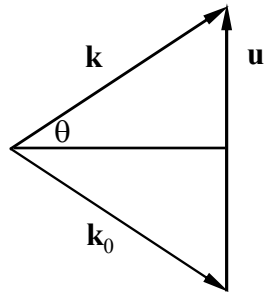
$$\mathbf{u} = h\mathbf{a}^* + k\mathbf{b}^* + l\mathbf{c}^*$$

reciprocal vector



$$|\mathbf{u}| = |h\mathbf{a}^* + k\mathbf{b}^* + l\mathbf{c}^*| = \frac{1}{d_{hkl}}$$

Bragg condition and Ewald sphere

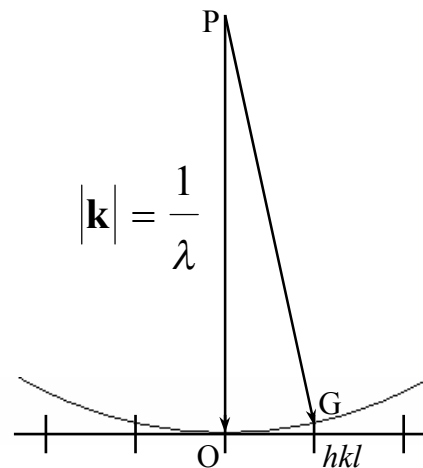
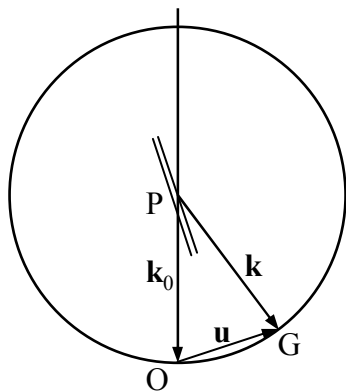


$$|\mathbf{u}| = 2|\mathbf{k}| \sin \theta = \frac{2 \sin \theta}{\lambda}$$



$$2d_{hkl} \sin \theta_{hkl} = \lambda$$

$$|\mathbf{u}| = \left| h\mathbf{a}^* + k\mathbf{b}^* + l\mathbf{c}^* \right| = \frac{1}{d_{hkl}}$$



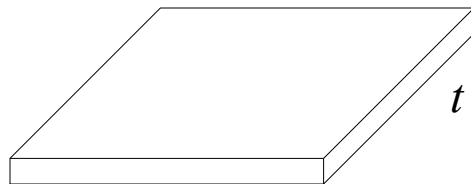
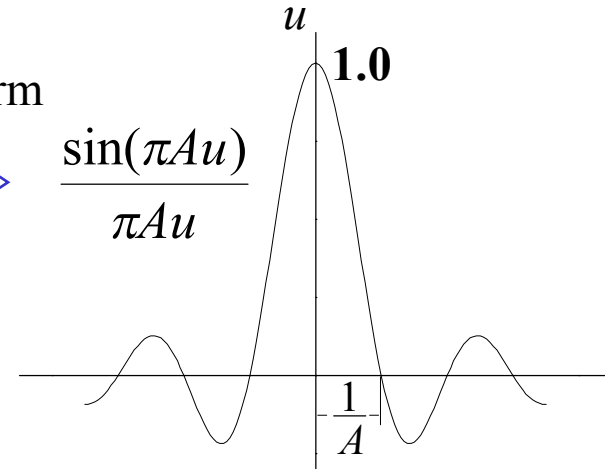
Shape factor



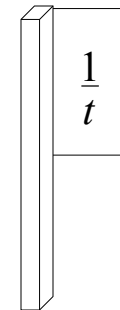
Fourier Transform



$$\frac{\sin(\pi A u)}{\pi A u}$$

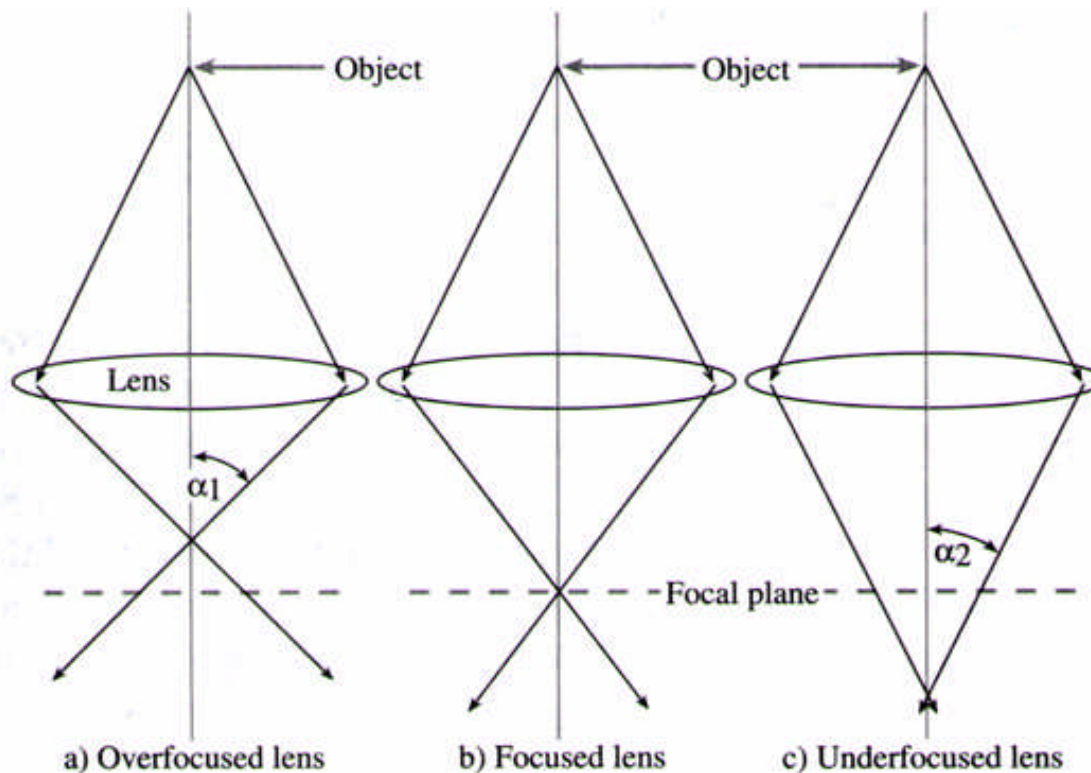


Sample shape



Shape of each reciprocal lattice point

Exciting the lens strength - focus



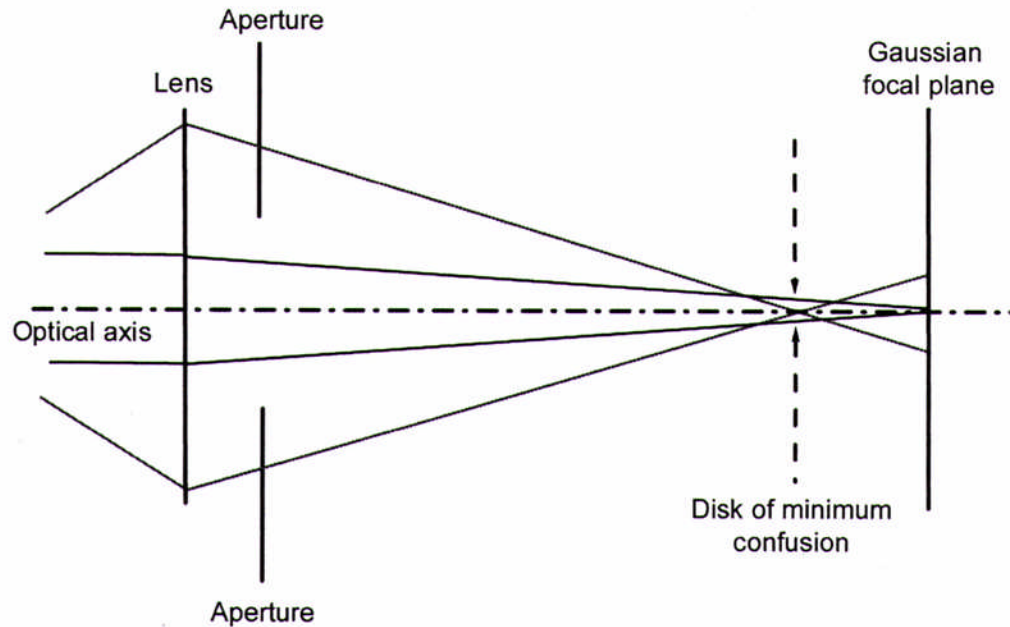
Lenses spatially fixed, but strength changeable

Phase shift factor in back focal plane

$$\exp\{i\pi\lambda\Delta f(u^2 + v^2)\} = \exp(i\chi_1)$$

The electromagnetic lenses are not perfect

Spherical aberration of lenses



$$\Delta r_0 = C_s \theta_0^3$$

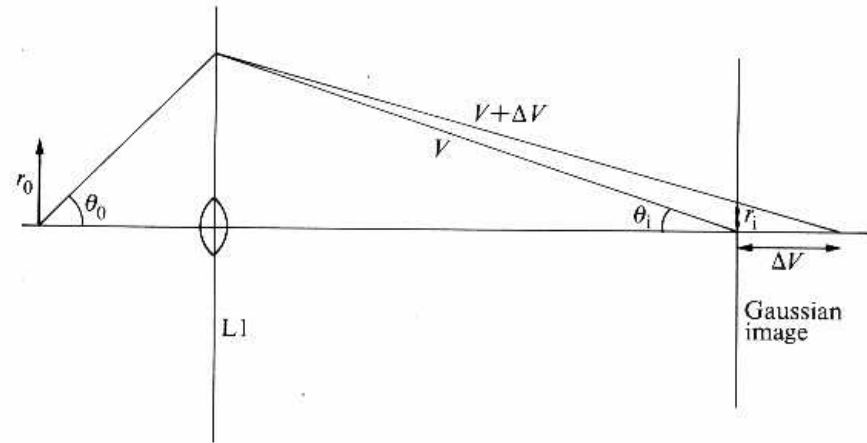
C_s : Spherical aberration coefficient

Phase shift in back focal plane
due to spherical aberration

$$\chi_2 = \frac{1}{2} \pi C_s \lambda^3 (u^2 + v^2)^2 = \exp(i\chi_2)$$

Chromatic aberration

Faster electrons are brought to a focus beyond the Gaussian image plane.



D: Standard deviation of Gaussian distribution due to the chromatic aberration

Envelope in back focal plane $\exp(-\chi_3)$

$$\chi_3 = \frac{1}{2} \pi^2 \lambda^2 D^2 \mathbf{H}^2$$

Beam divergence

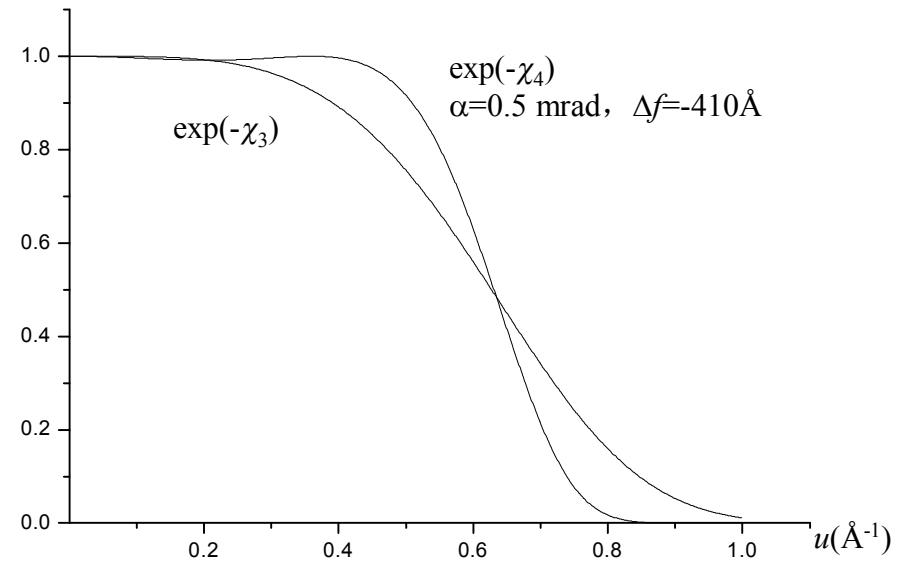
Paralell incident beam (ideal condition)

Divergence angle $\alpha \sim 0.5$ mrad (real condition)

Envelope in back focal plane

$$\exp(-\chi_4)$$

$$\chi_4 = \pi^2 \alpha^2 \mathbf{H}^2 (C_s \lambda^2 \mathbf{H}^2 + \Delta f)^2$$



Transfer function $W(\mathbf{H}) = \exp(i\chi_I) \exp(-\chi_{II})$

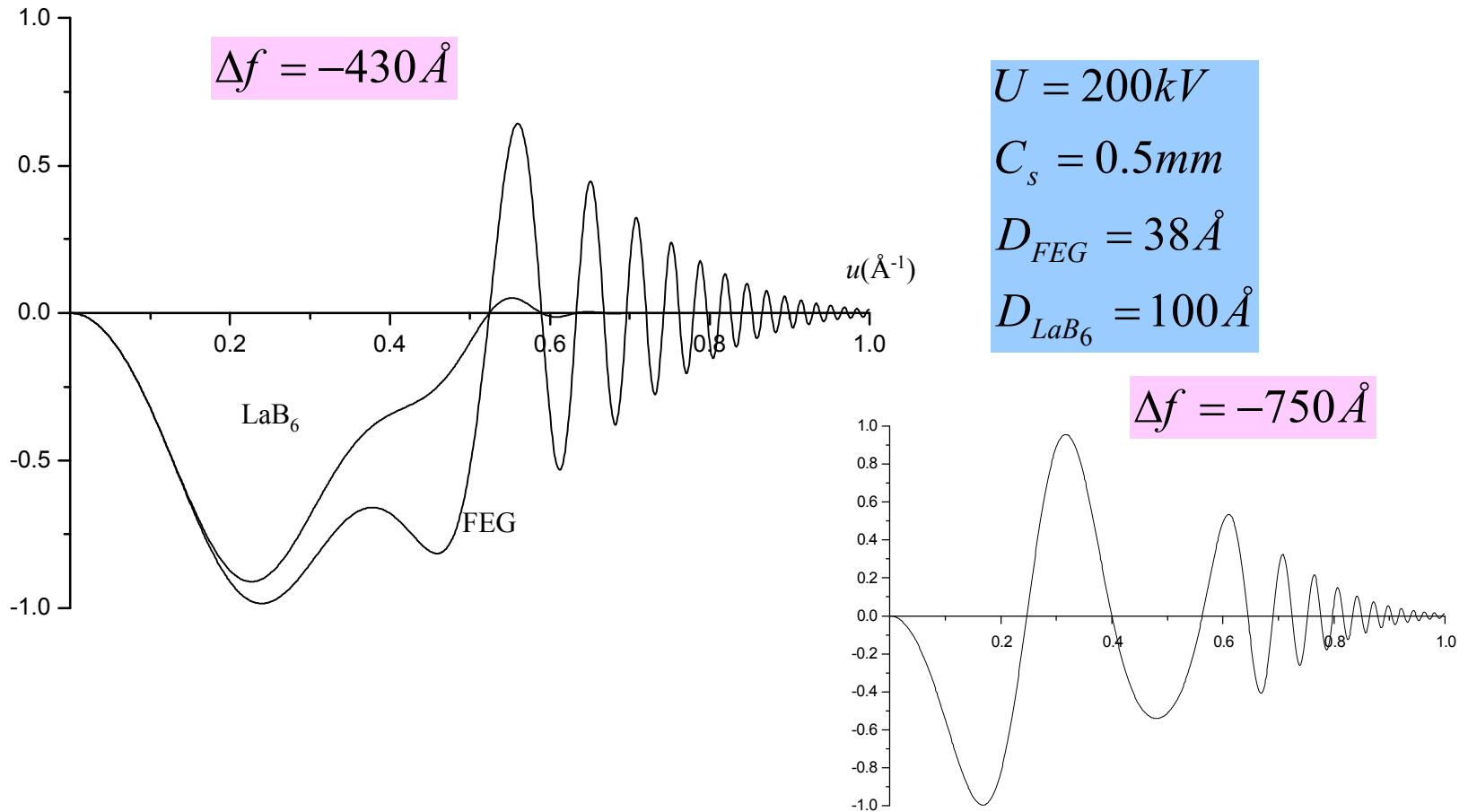
Electron wave function and intensity in the image plane

$$\psi_{image} = F^{-1} \{ F [\psi_{exit}] \cdot W(\mathbf{H}) \}$$

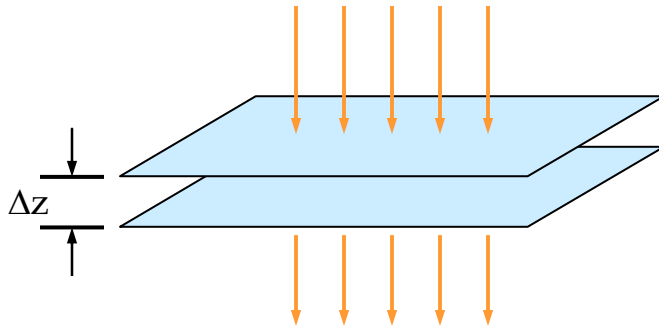
$$I = \psi_{image} \cdot \psi_{image}^*$$

Contrast Transfer Function (CTF)

$$\sin(\chi_I) \exp(-\chi_{II})$$



Phase contrast in TEM



Exit wave:
$$\psi_e(\mathbf{r}) = e^{-i\sigma V_p(\mathbf{r})} \approx 1 - i\sigma V_p(\mathbf{r})$$

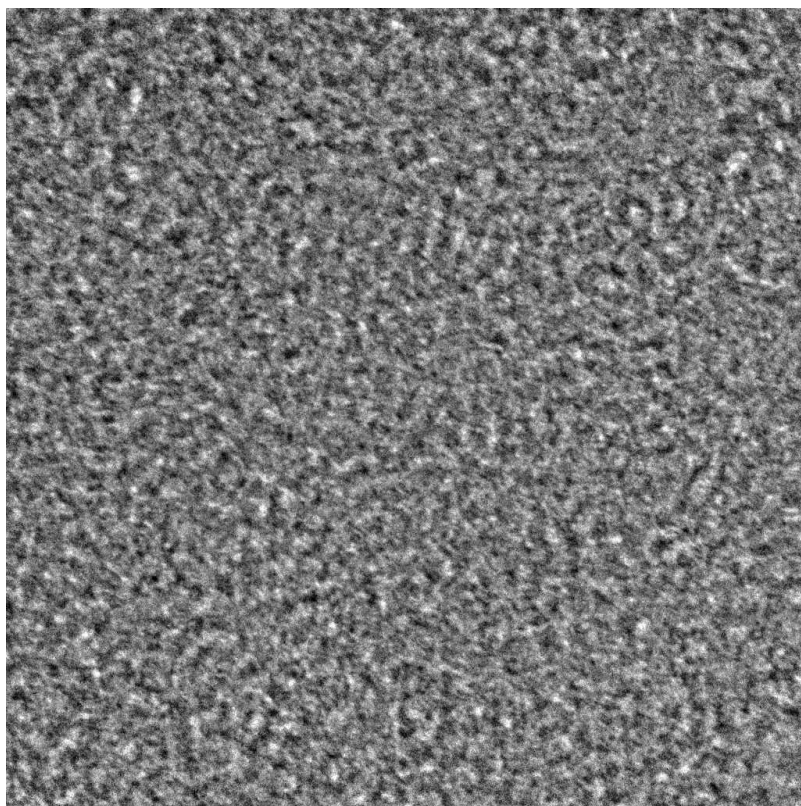
Assuming weak-phase object approximation

V_p : scattering potential

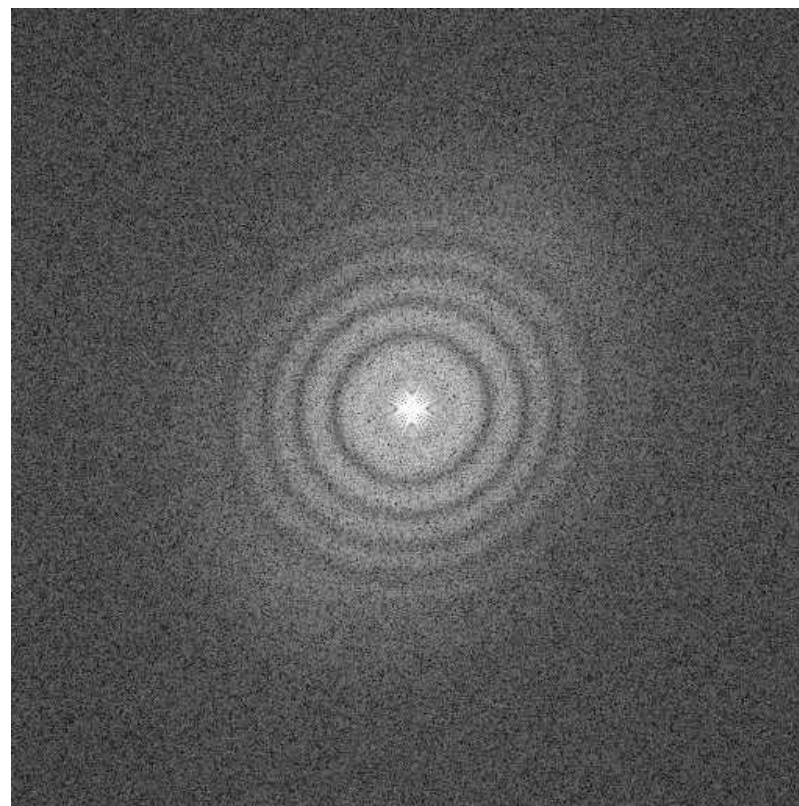
Final intensity:
$$I(\mathbf{r}) \approx 1 + 2\sigma V_p(\mathbf{r}) * \mathcal{F}^{-1}\{CTF\}$$

Picturing the Contrast Transfer Function

Amorphous Thin Carbon Film



FT
→



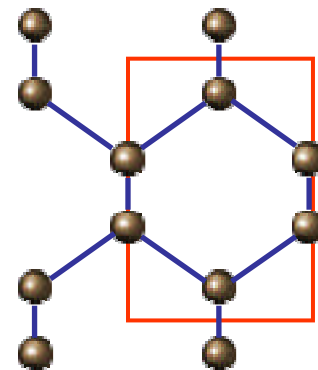
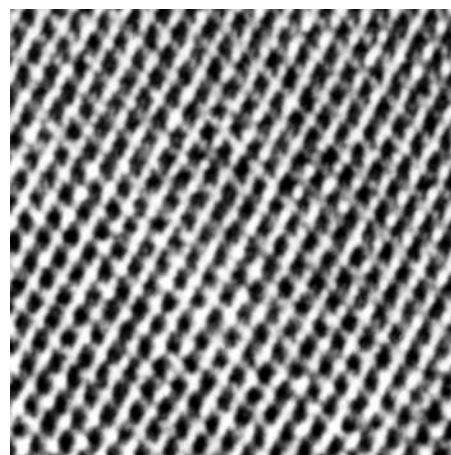
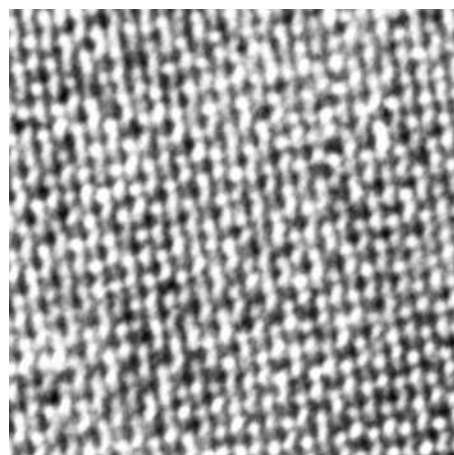
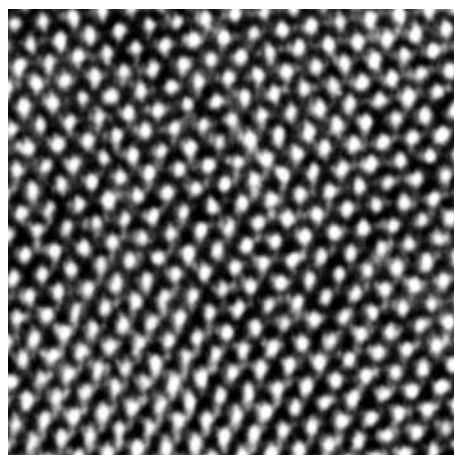
Real Space $I(\mathbf{r}) \approx 1 + 2\sigma V_p(\mathbf{r}) * \mathbf{F}^{-1}\{CTF\}$

Reciprocal Space

Image interpretation

Only for **thin crystal (WPOA)** and the focus value close to **Scherzer focus**, the contrast of HREM image can be interpreted as crystal structure up to point resolution.

In general, the black or white dots in HREM image **DO NOT** correspond to atoms or atom groups.



Si [110] image with different defocus values

Simulated HRTEM images

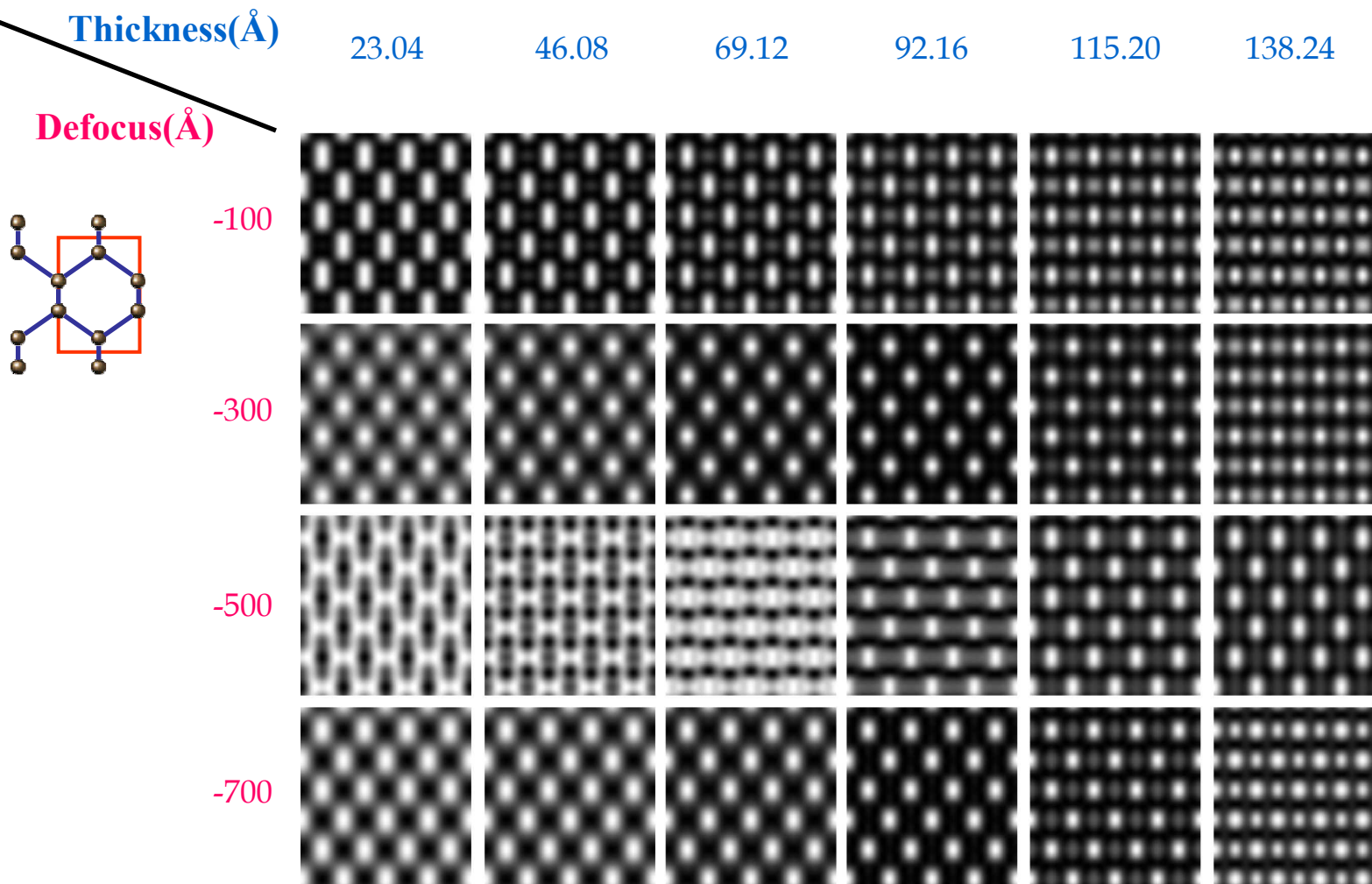
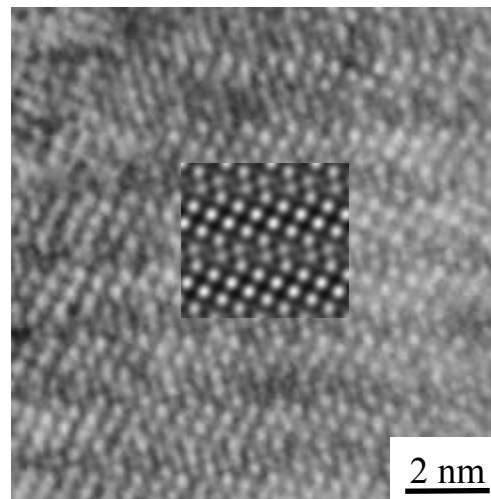
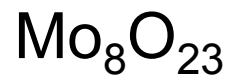
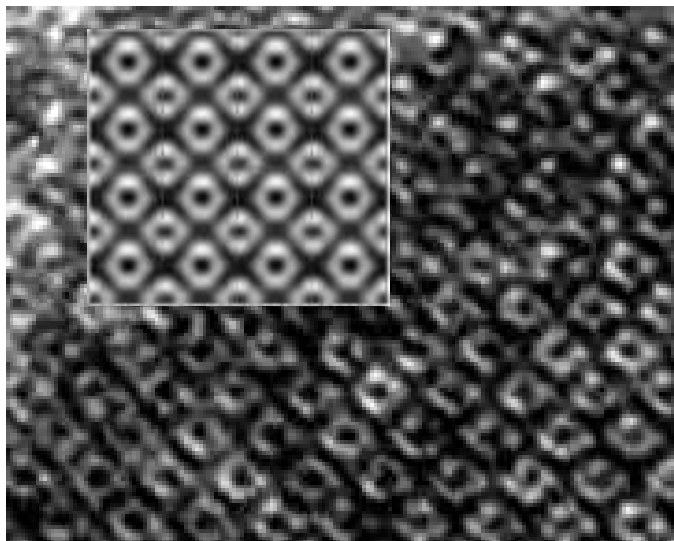
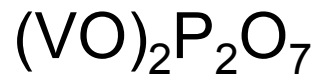
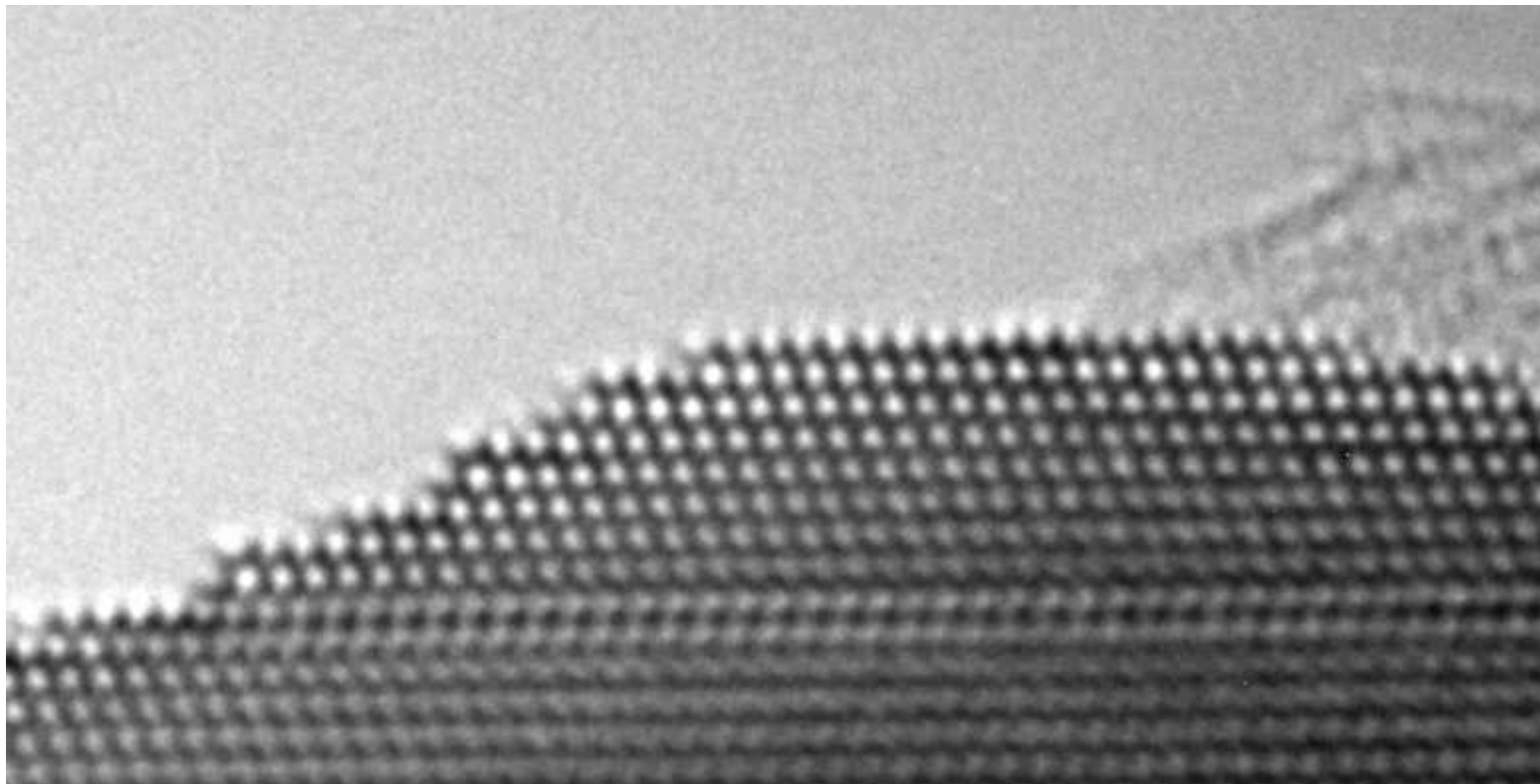


Image contrast matching

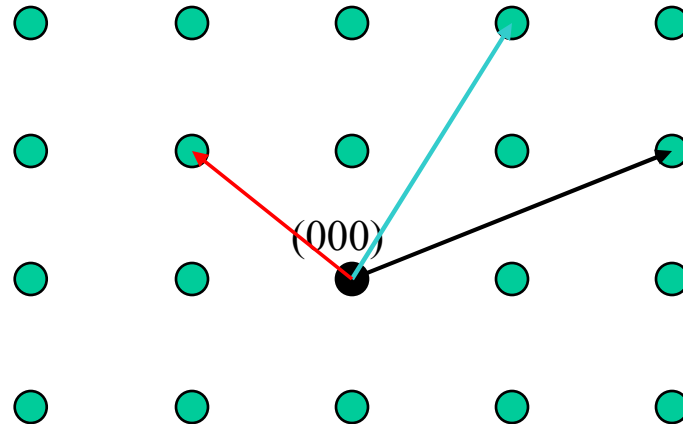
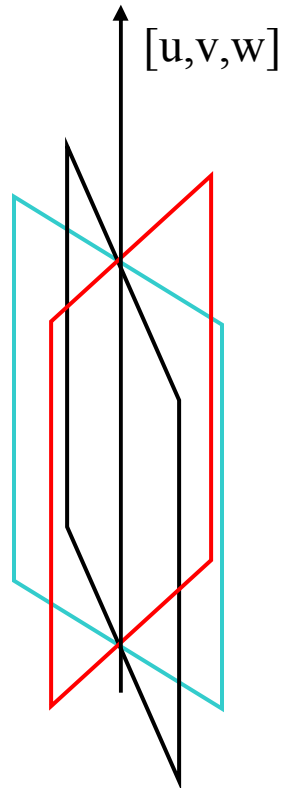


HRTEM-profile imaging



Electron diffraction

Zone axis

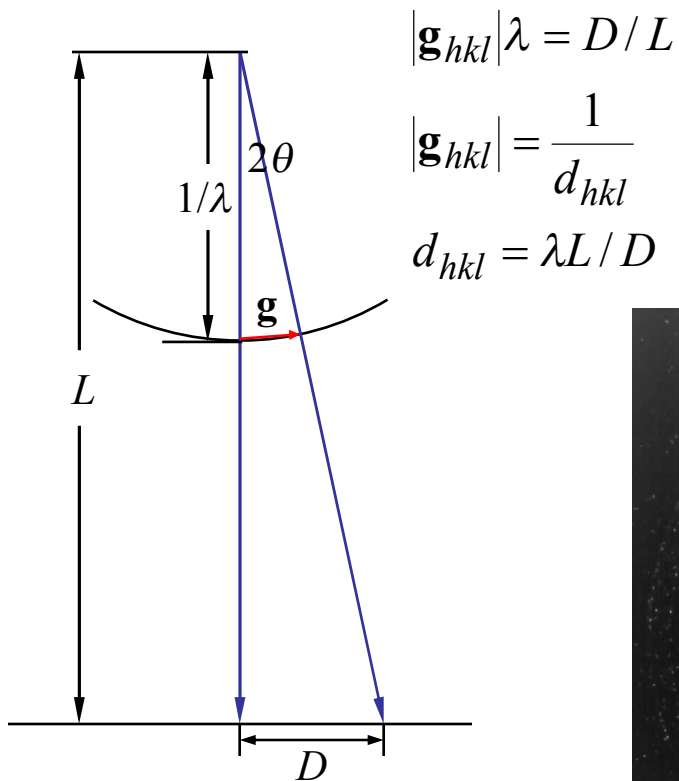


$$[u, v, w] \perp (h, k, l)$$

Example: cubic structure, (100), (110), (120), (340)..... planes belong to [001] zone axis

Electron diffraction

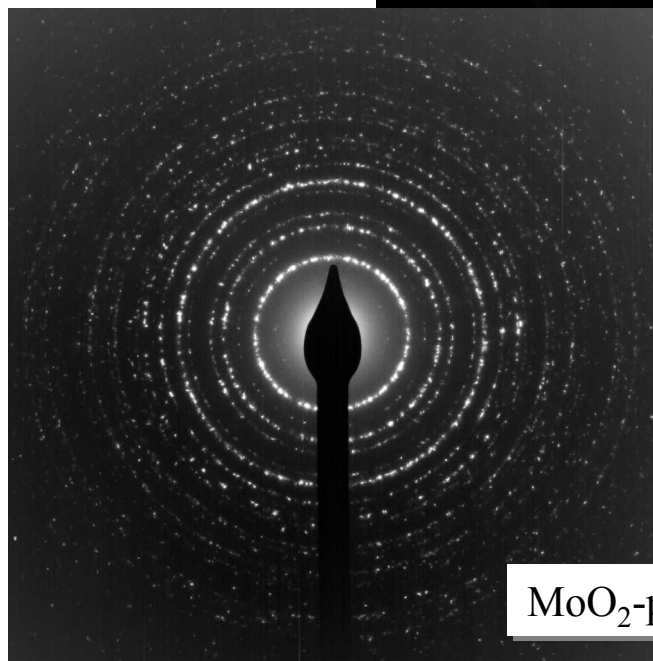
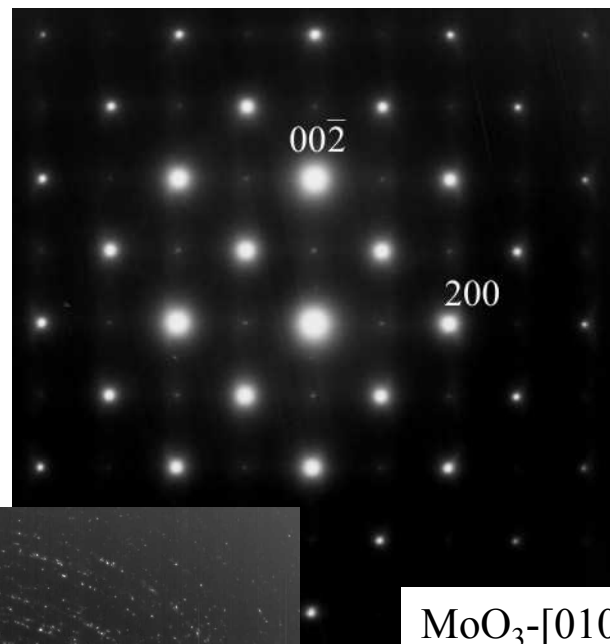
Camera length



$$|\mathbf{g}_{hkl}| \lambda = D / L$$

$$|\mathbf{g}_{hkl}| = \frac{1}{d_{hkl}}$$

$$d_{hkl} = \lambda L / D$$

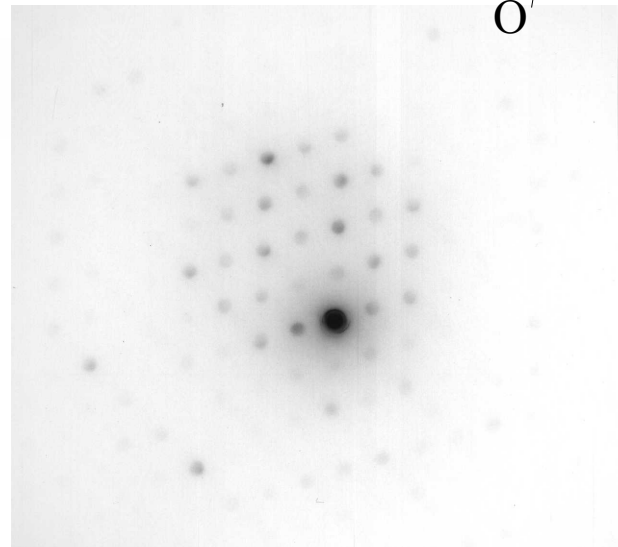
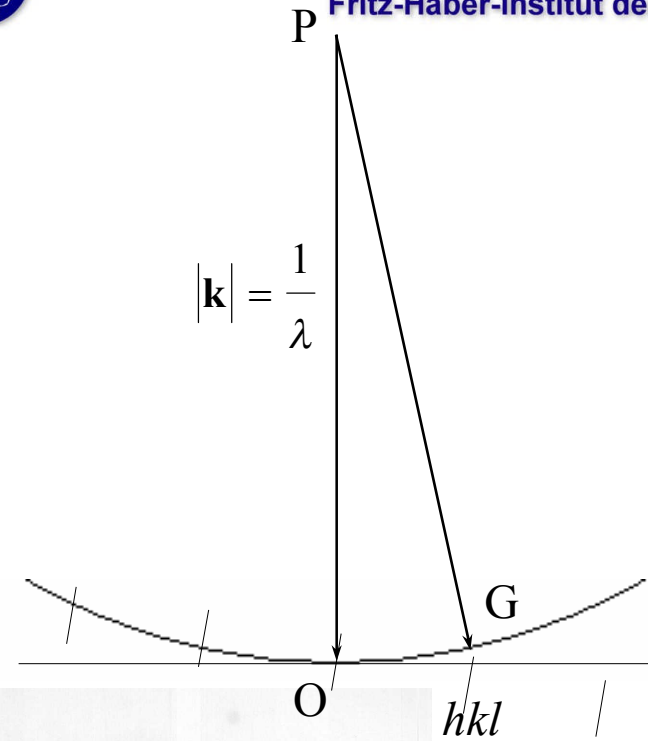
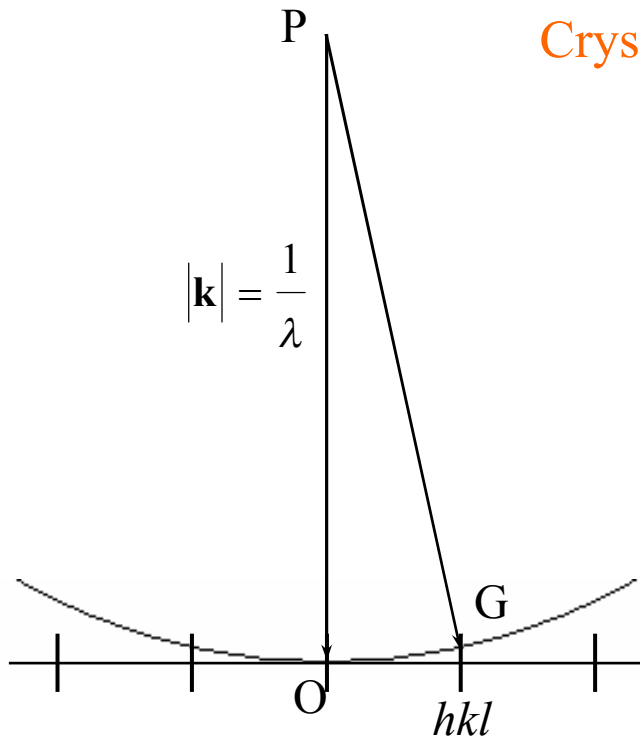


MoO_3 -[010]

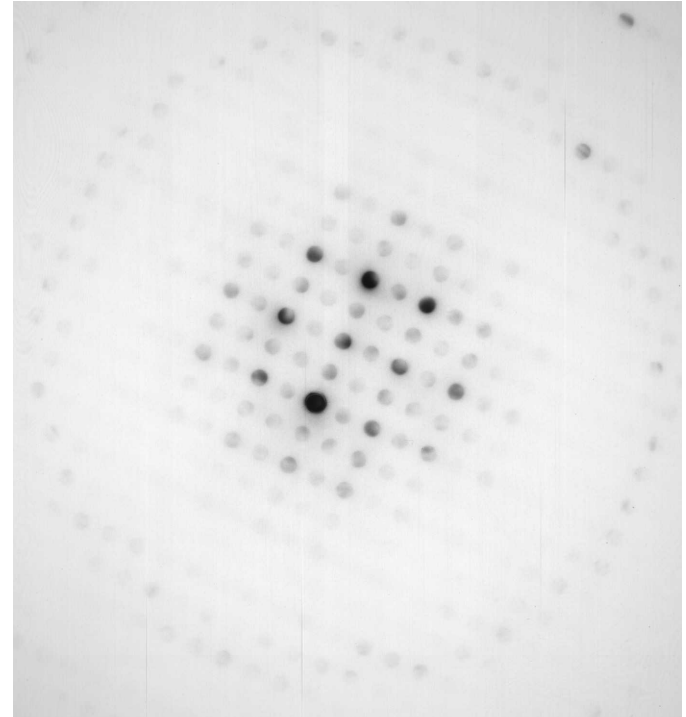
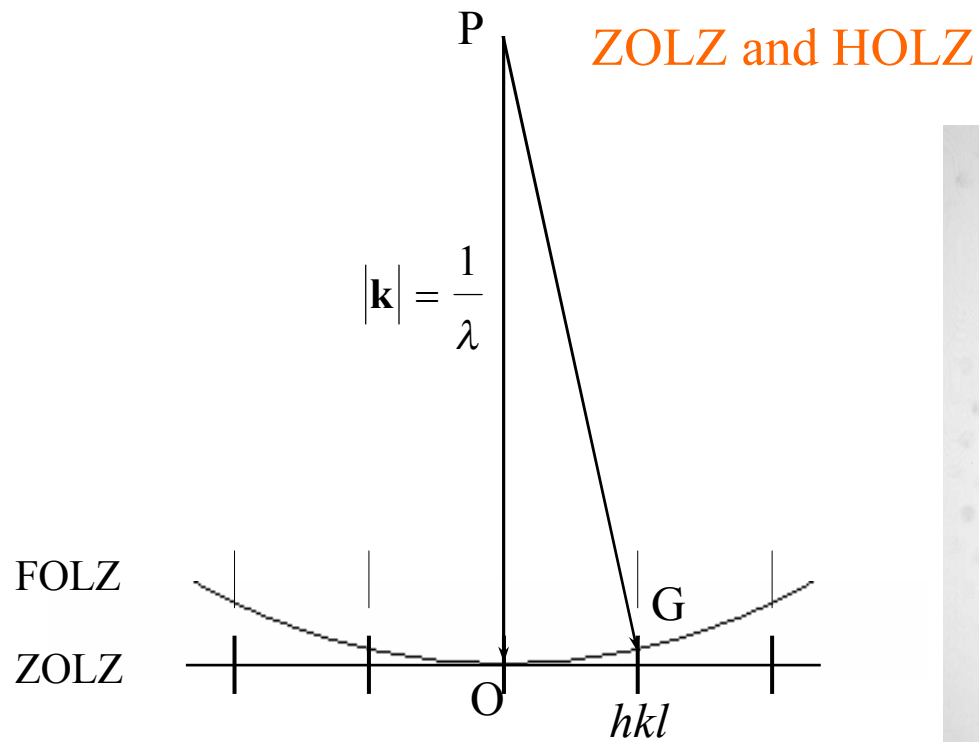
MoO_2 -polycrystalline

Electron diffraction

Crystal tilt

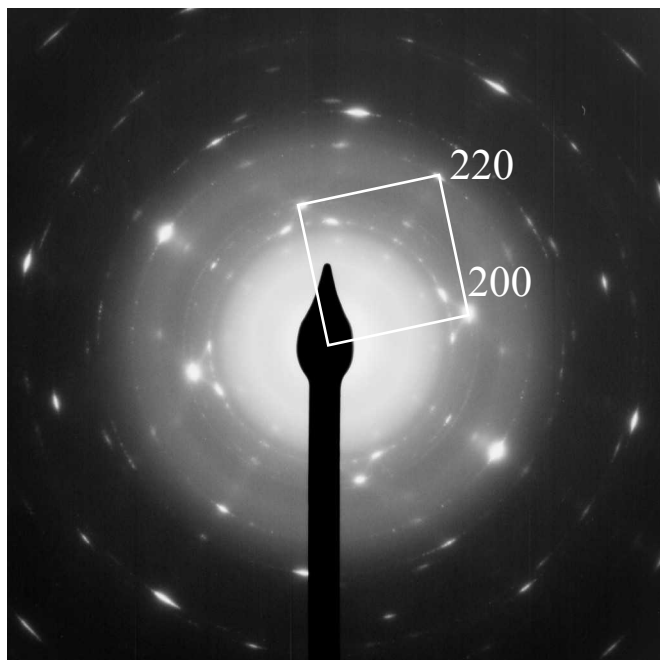


Electron diffraction



Electron diffraction

Calibration by a known structure

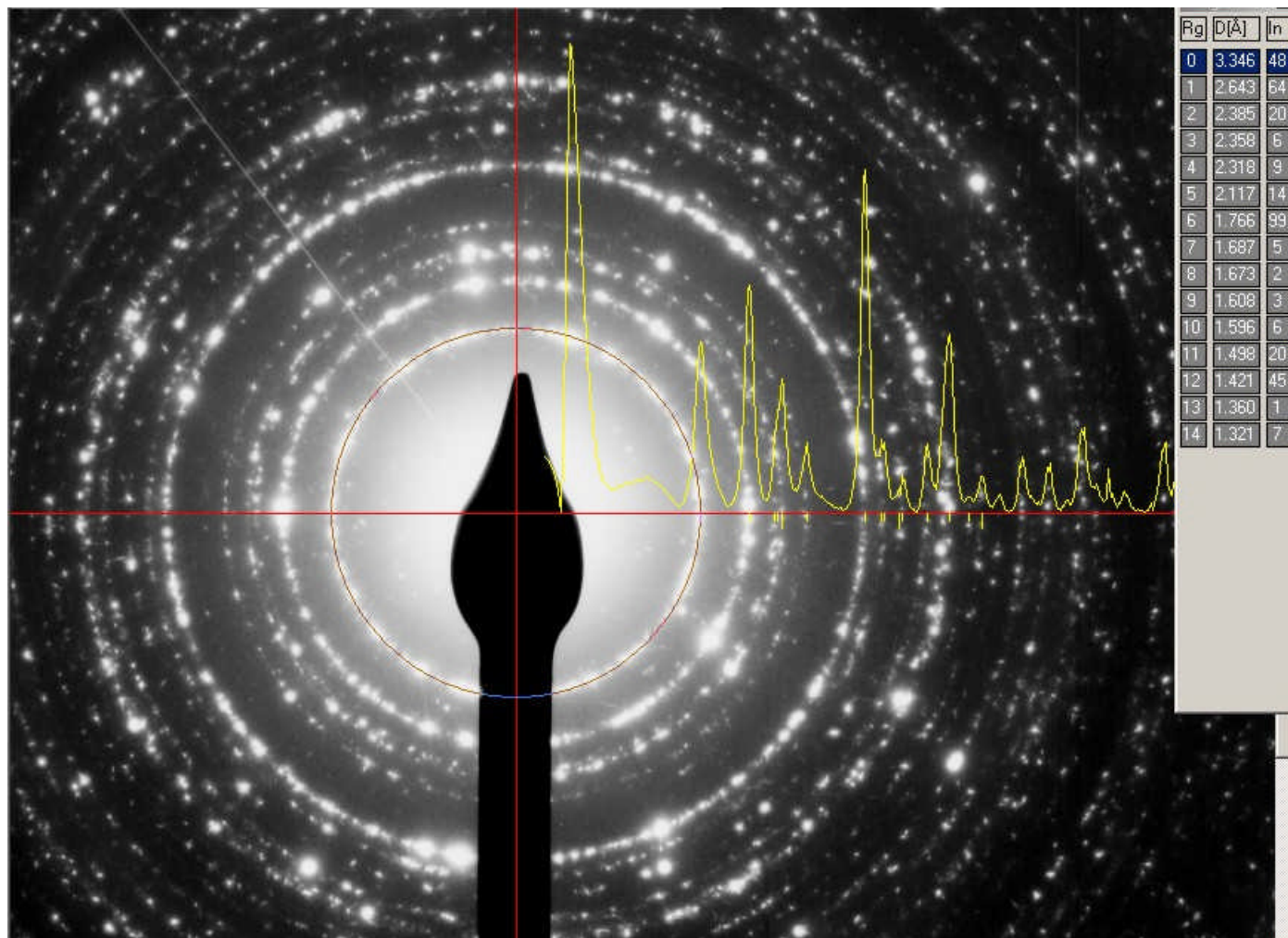


If a $h_0k_0l_0$ diffraction from a known structure can be determined in a diffraction pattern and its distance to the center is measured as u_0 , for any other diffraction with distance u to the center, the lattice spacing d is given by:

$$d = u_0 d_{h_0k_0l_0} / u$$

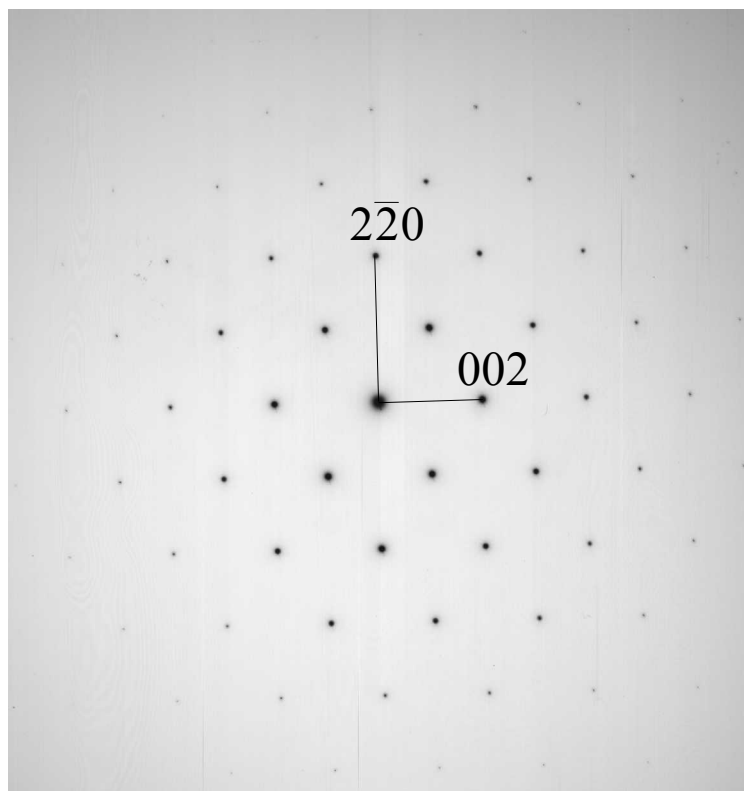
Electron diffraction

Indexing of a ring pattern



Electron diffraction

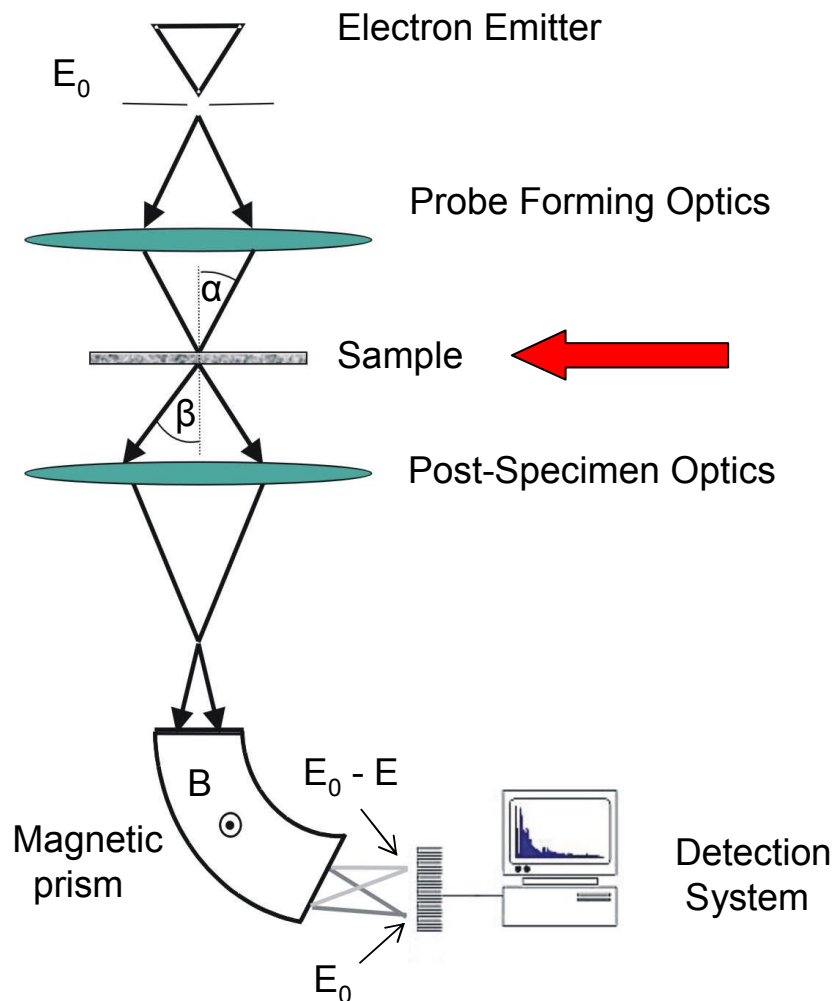
Indexing of a single crystal pattern



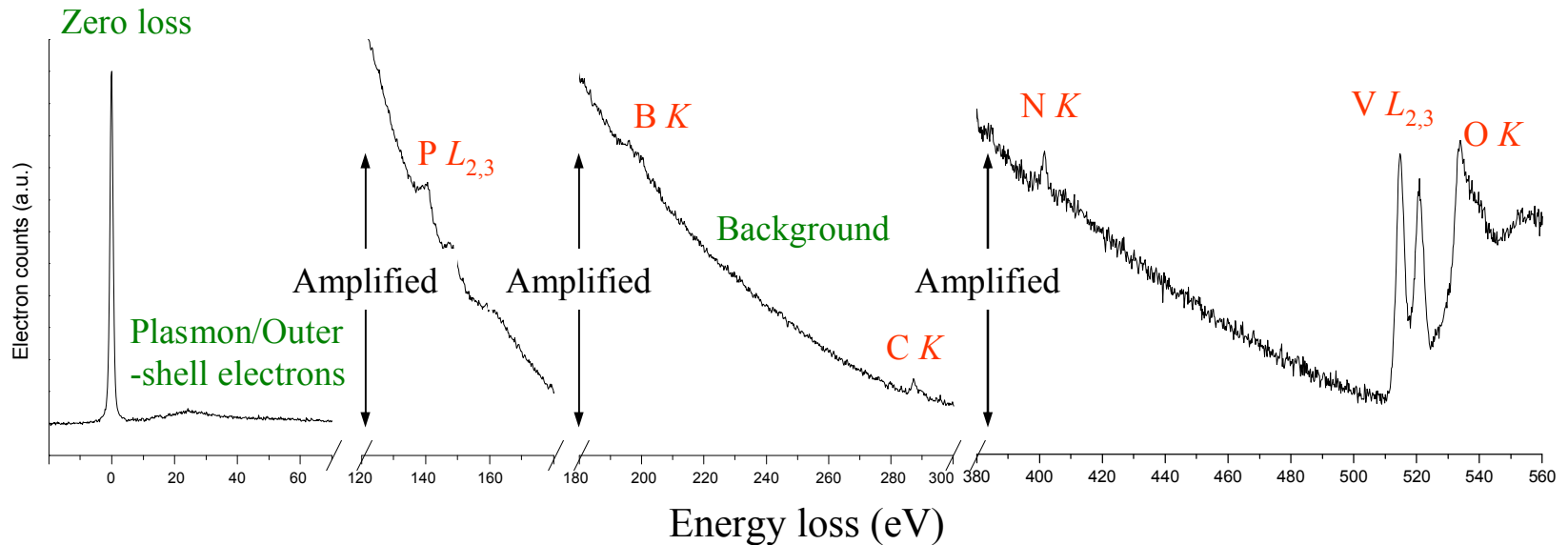
- Two sets of lattice planes and the angle in between
- Using extinction rules
- Using diffraction pattern on other zone axis
- Simulation

Cubic ZrO_2 (fluorite structure) on $[110]$ projection

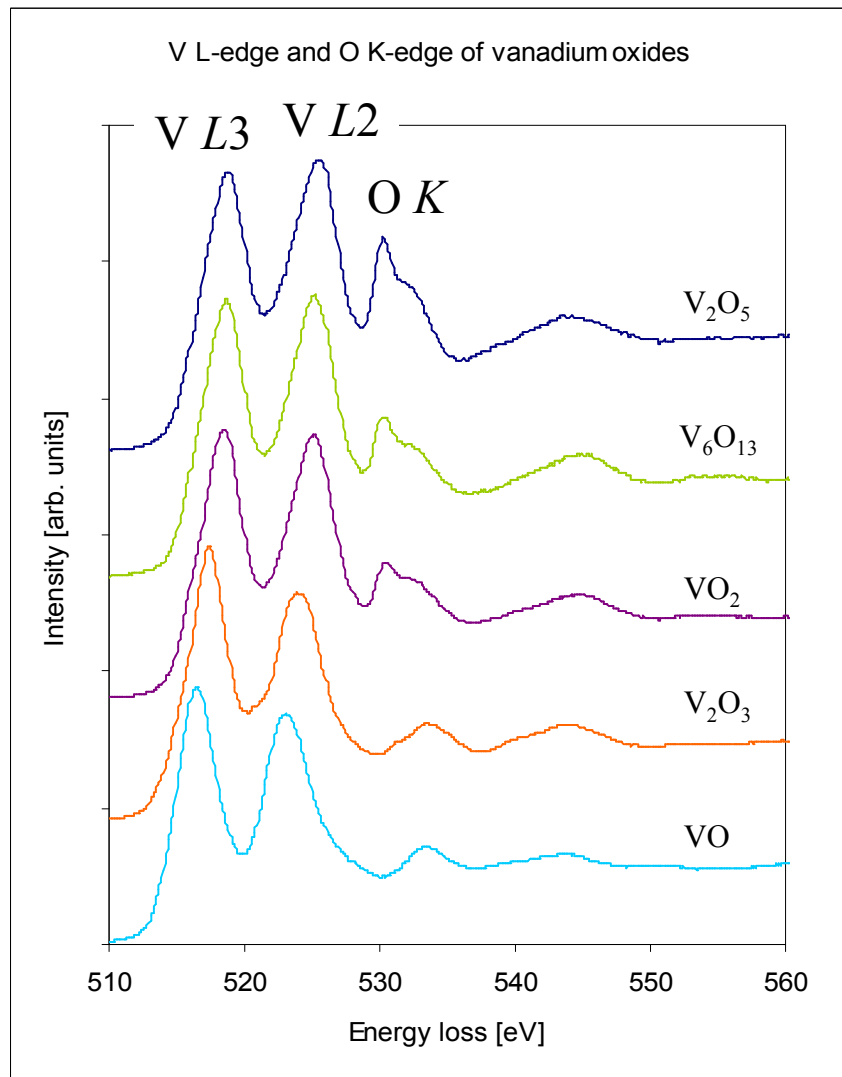
Electron Energy Loss Spectroscopy (EELS)



EELS

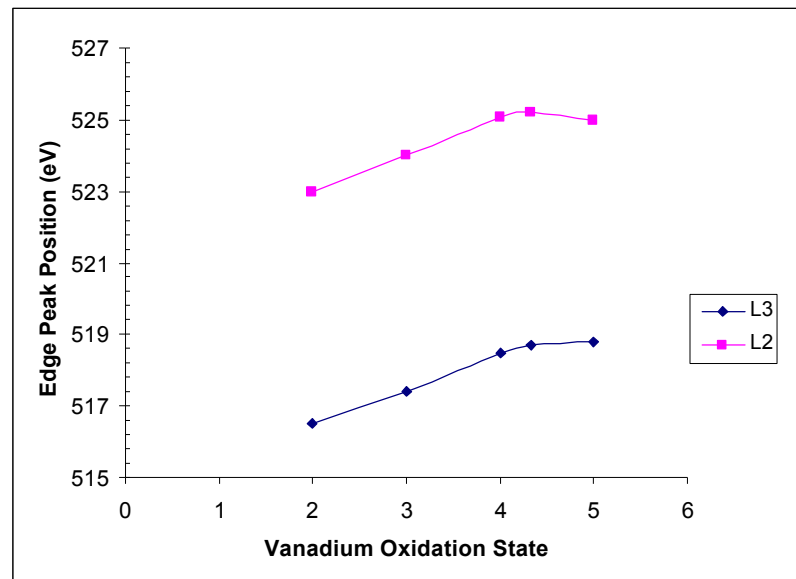


- zero-loss peak
- plasmon peak
- Inner-shell ionization edges, low intensity
- Near edge structure on top of edges
- background
- Plural scattering



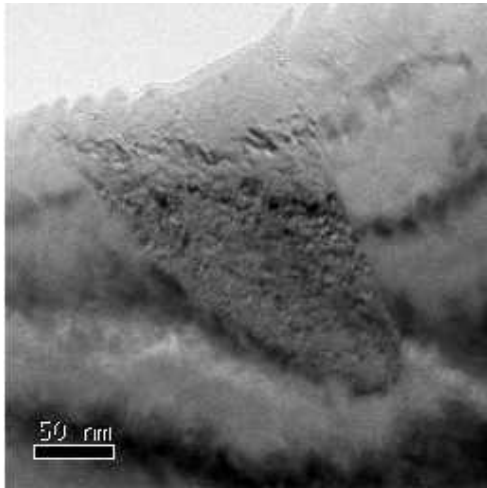
ELNES of Vanadium Oxides

Correlation of peak positions of the vanadium L-edges with the oxidation states of vanadium atoms in various vanadium oxides



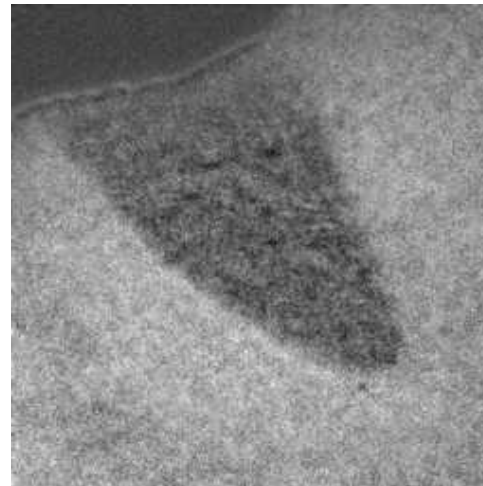
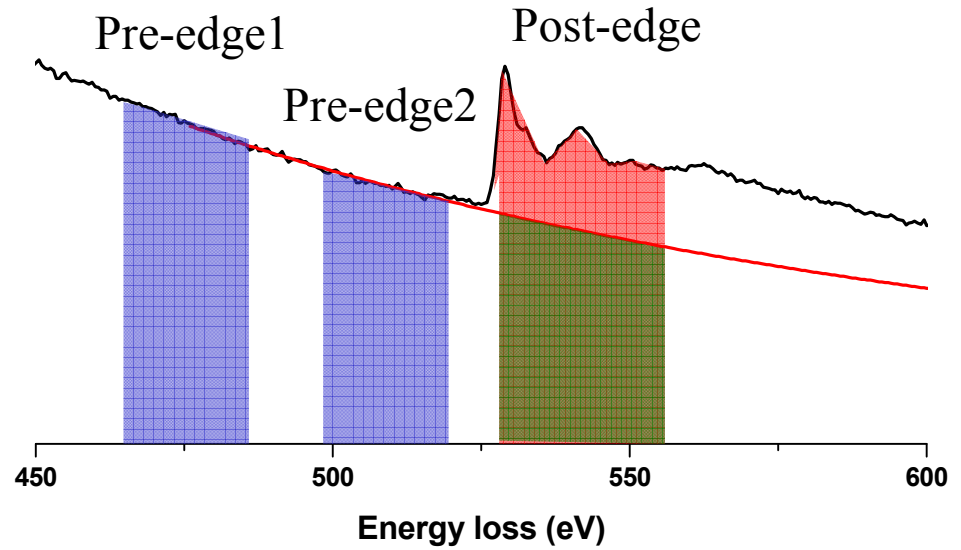
EELS

Element mapping

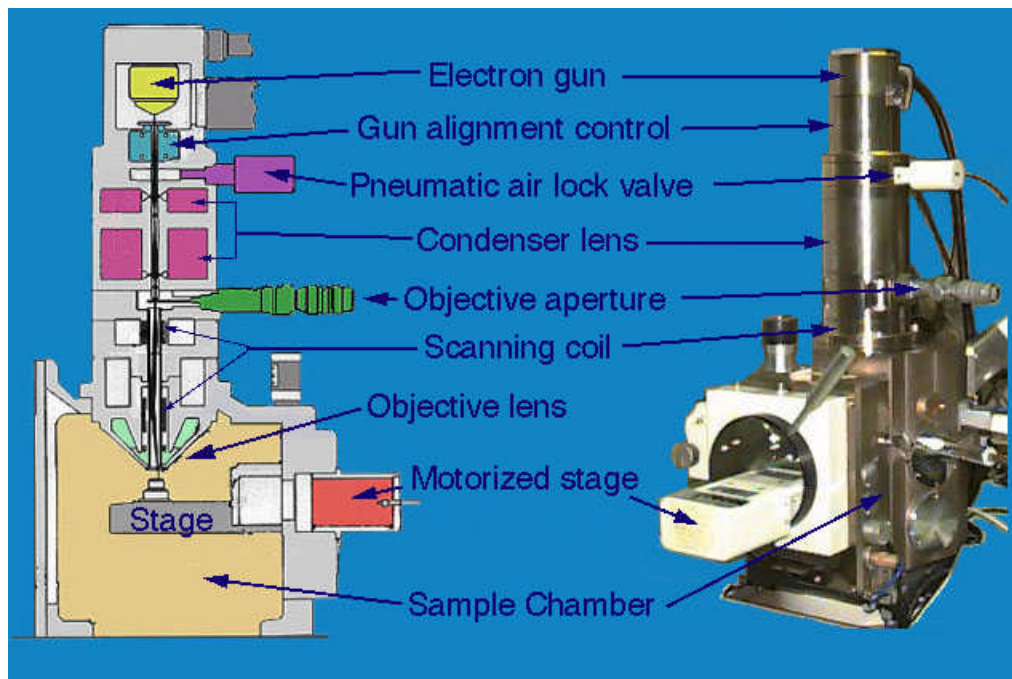


TEM image of ZrN/ZrO₂

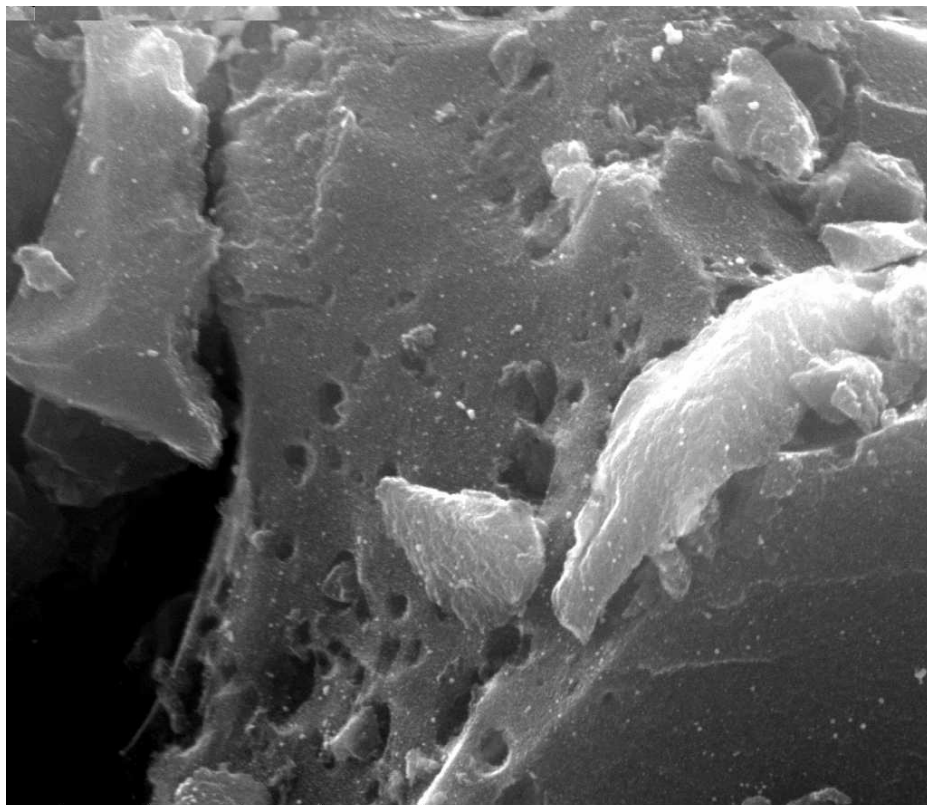
Oxygen map



SEM

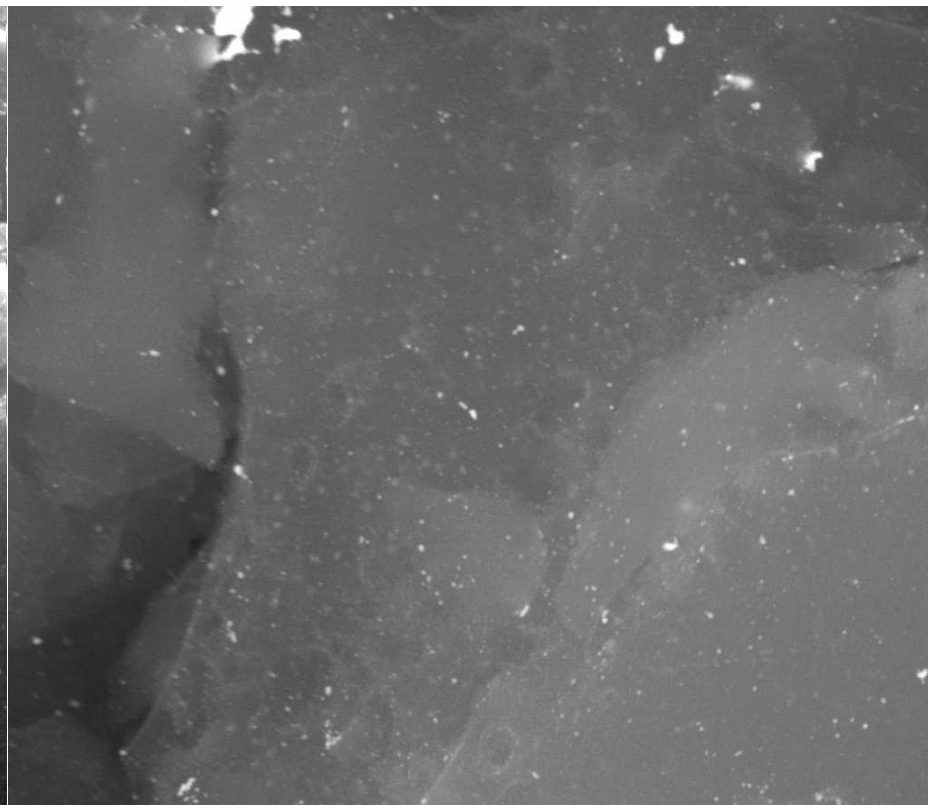


SEM



Det	HV	WD	Mag	File
ETD	15.0 kV	9.8 mm	40095x	01-se.tif*

1.0 μm
1Au1Pd



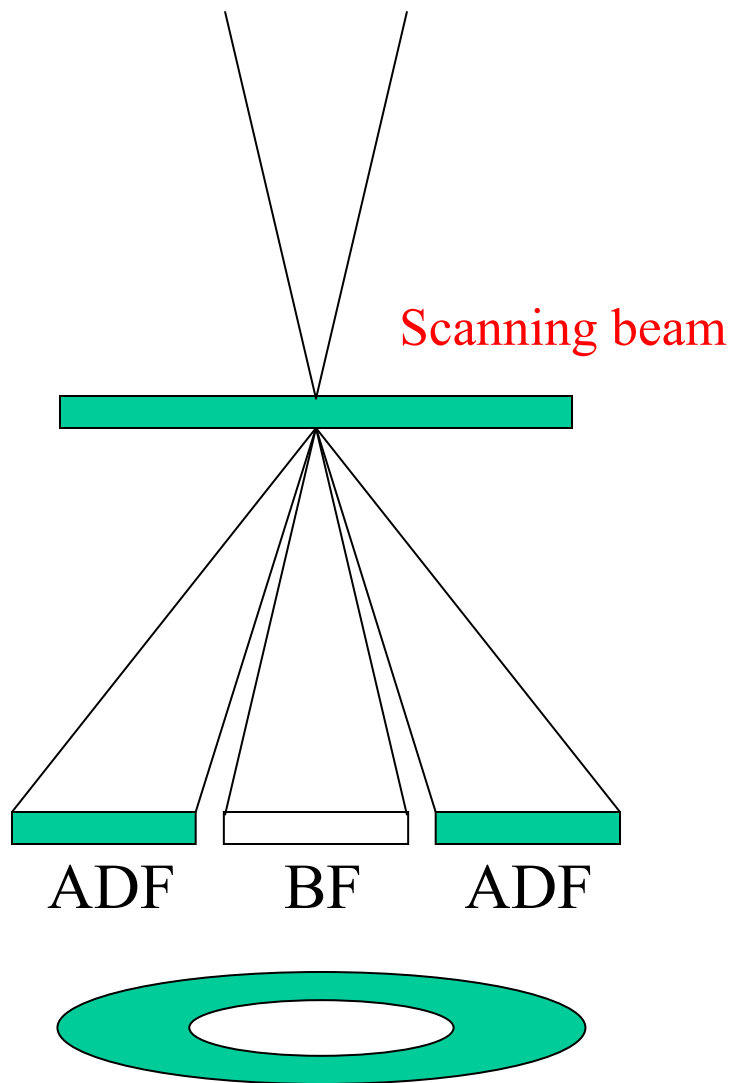
Det	HV	WD	Mag	File
SSD	15.0 kV	9.8 mm	40095x	01-bs.tif*

1.0 μm
1Au1Pd

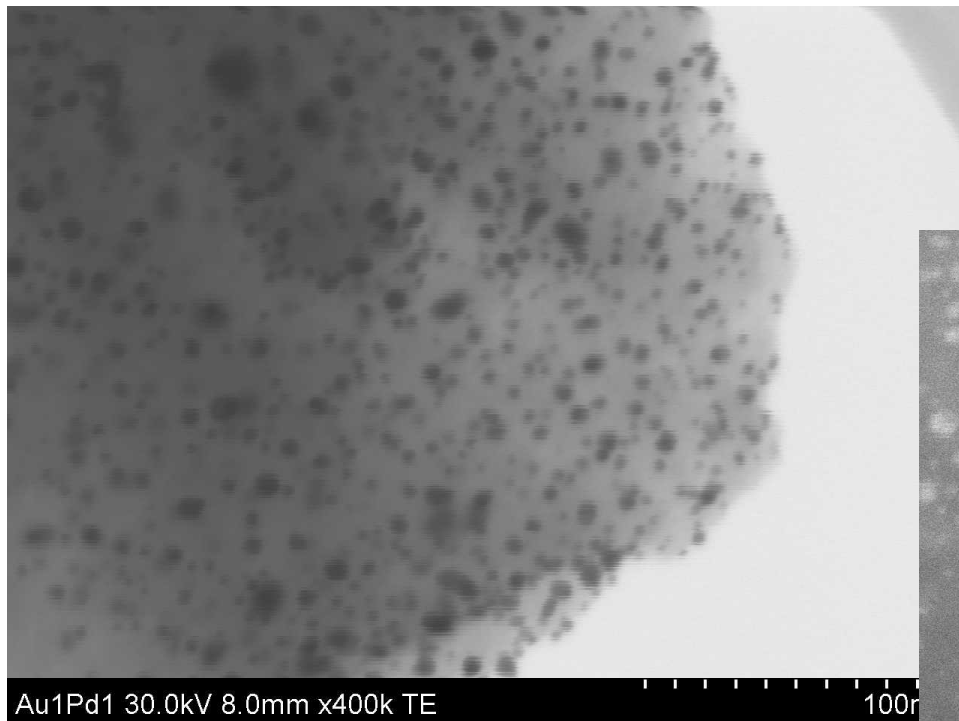
Secondary electron

Back scattered electron

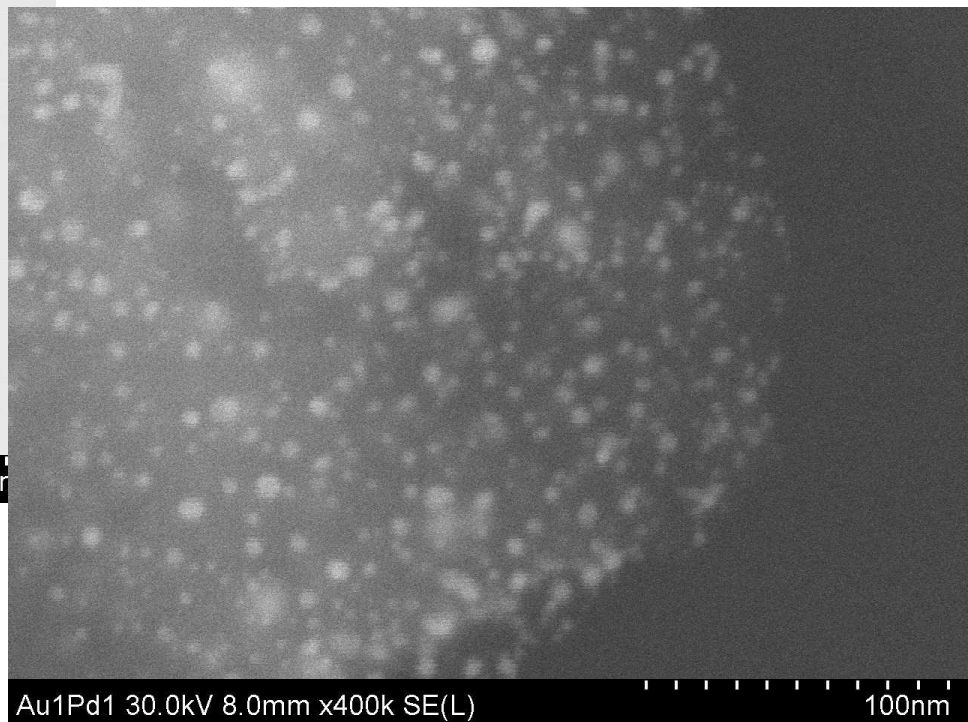
STEM



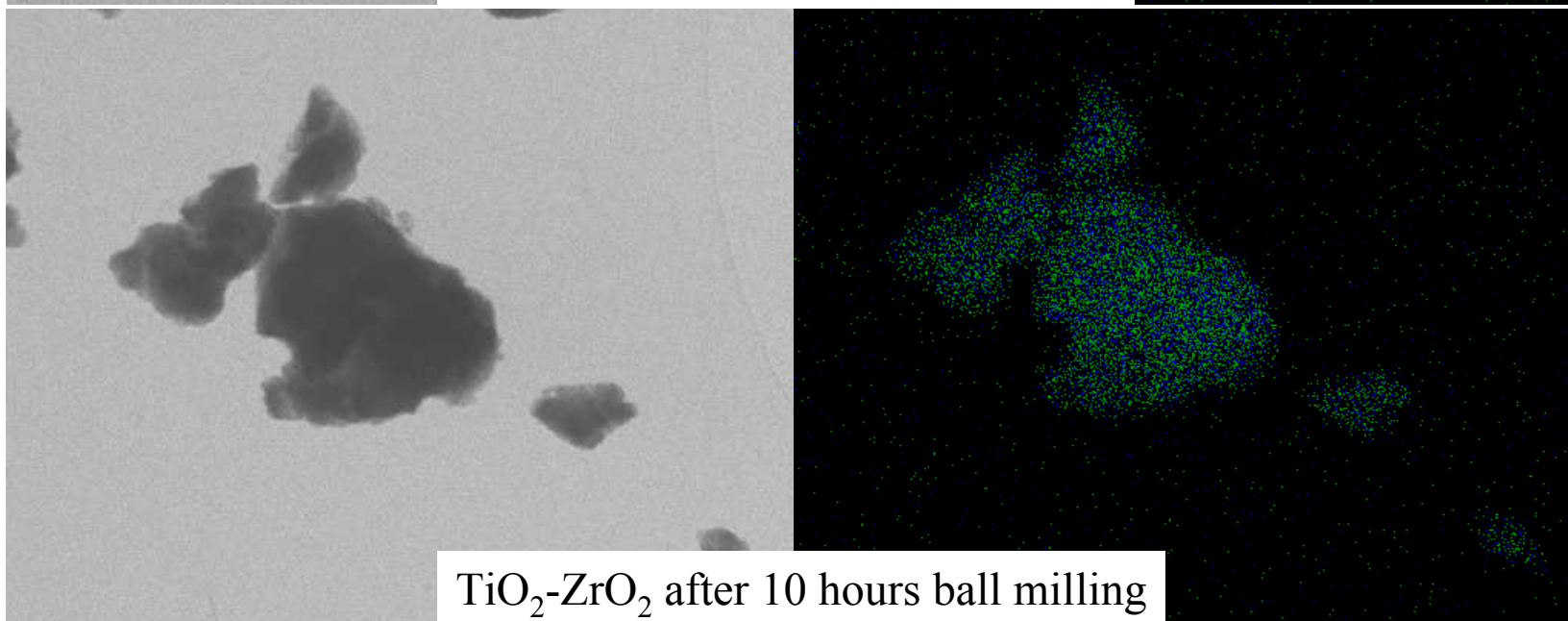
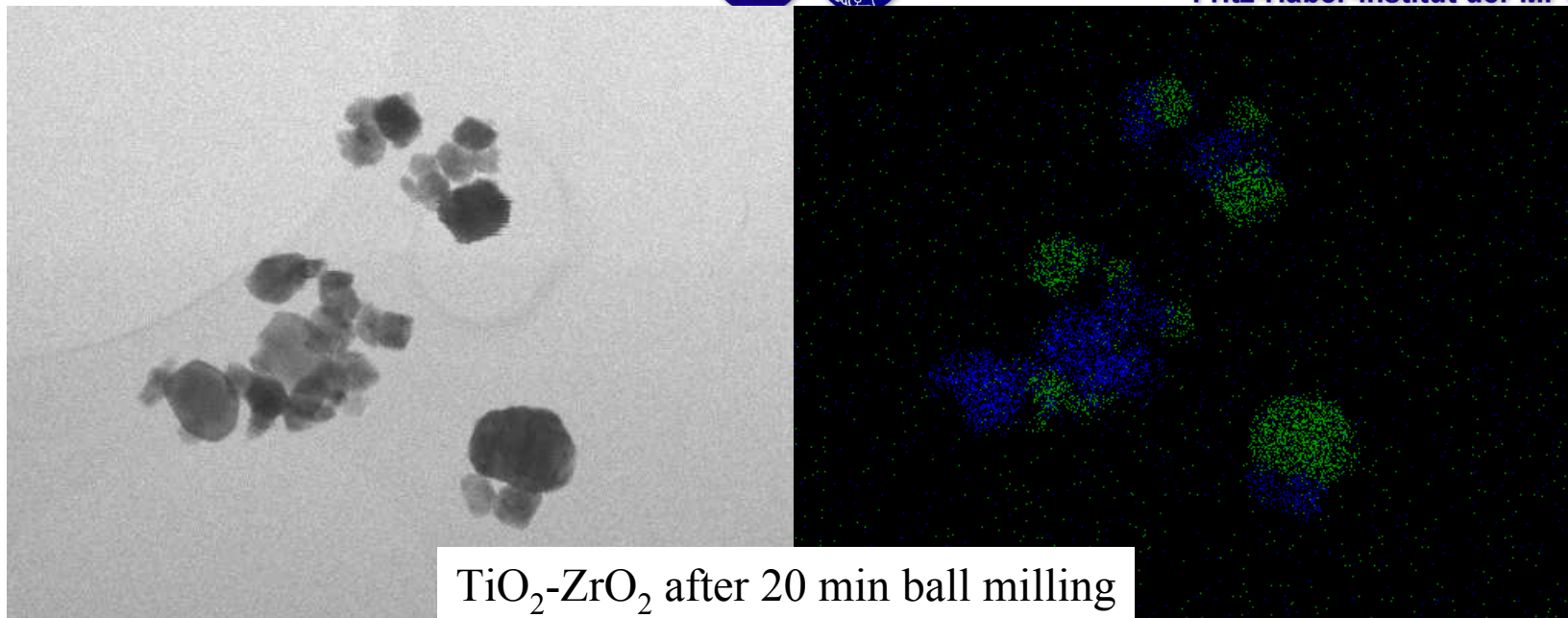
STEM



BF



DF



Application in catalytic systems

Important heterogeneous catalysts

Information of interests

Supported metal

particle size effects; metal-substrate interaction;
structural change under chemical treatments

Transition metal oxide

reduction behavior; defects structures

Zeolites (porous structure)

3D structure; intergrowth of different zeolitic
structures; guest species inside a zeolitic host

Carbon nanofibers as support

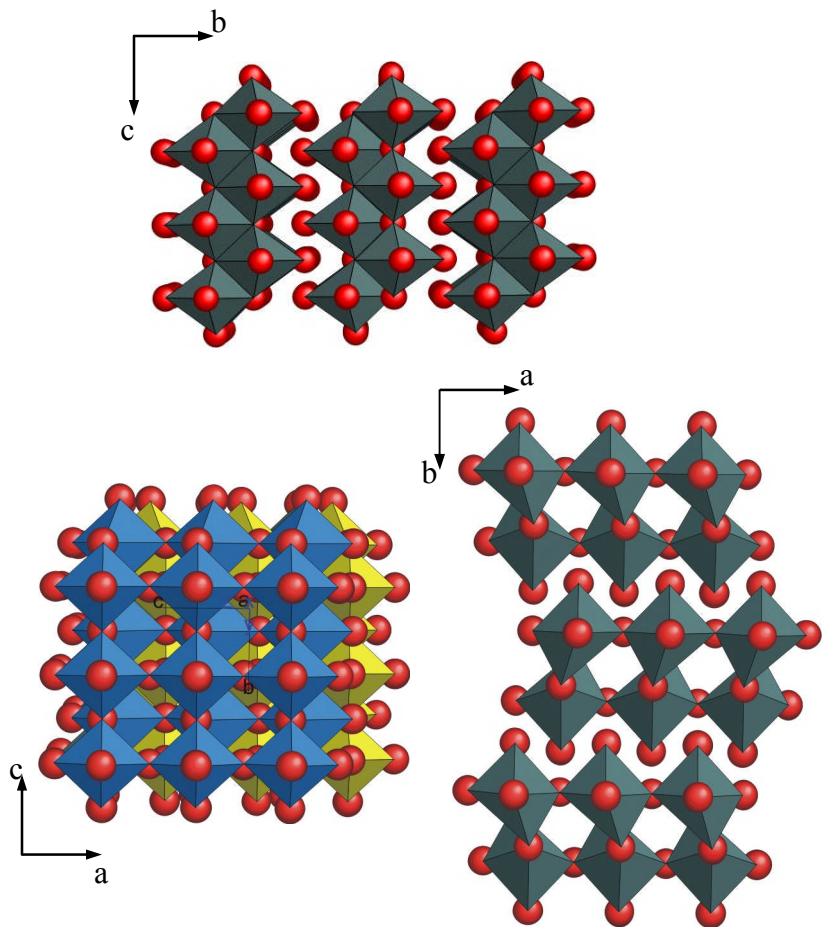
structure and growing mechanisms



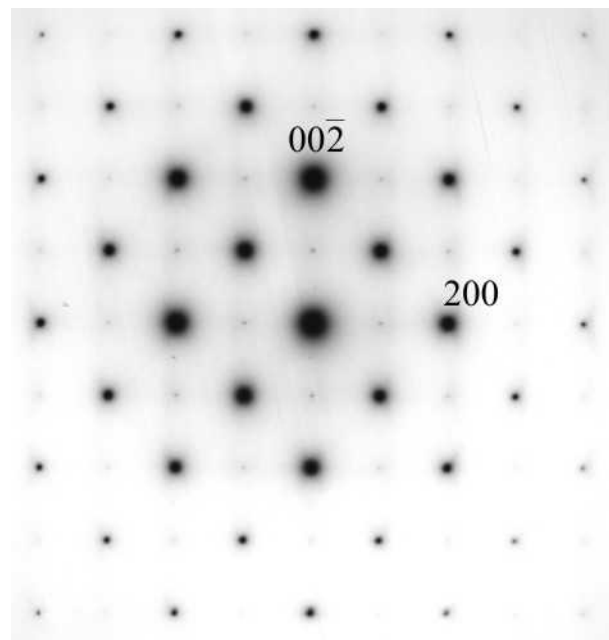
Application in catalytic systems

Reduction of MoO_3 induced by electron beam irradiation

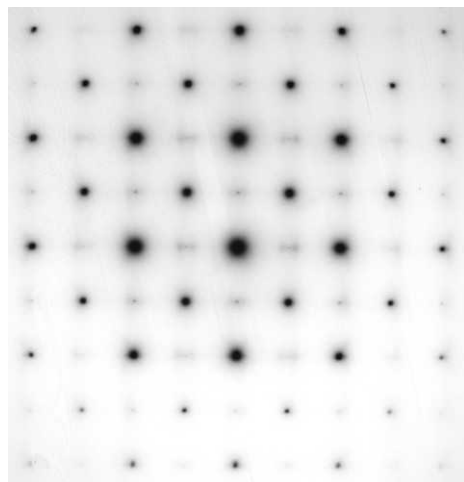
Reduction of MoO_3 by electron beam irradiation



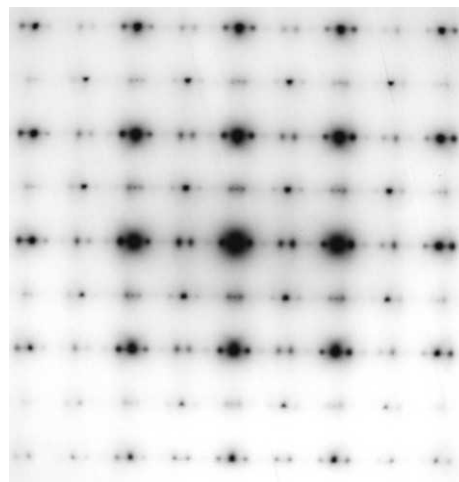
Structure of MoO_3



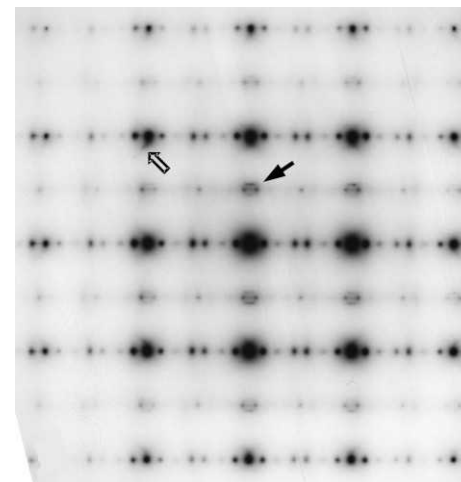
Diffraction of MoO_3 on $[010]$ projection



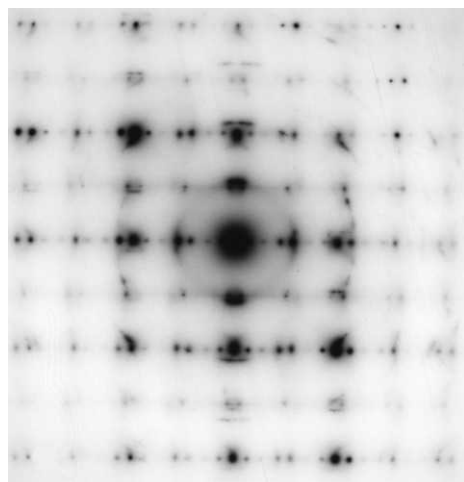
After irradiation of 10 min



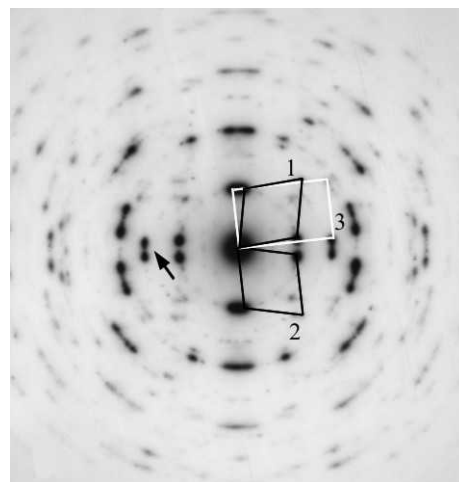
60 min



120 min



200 min

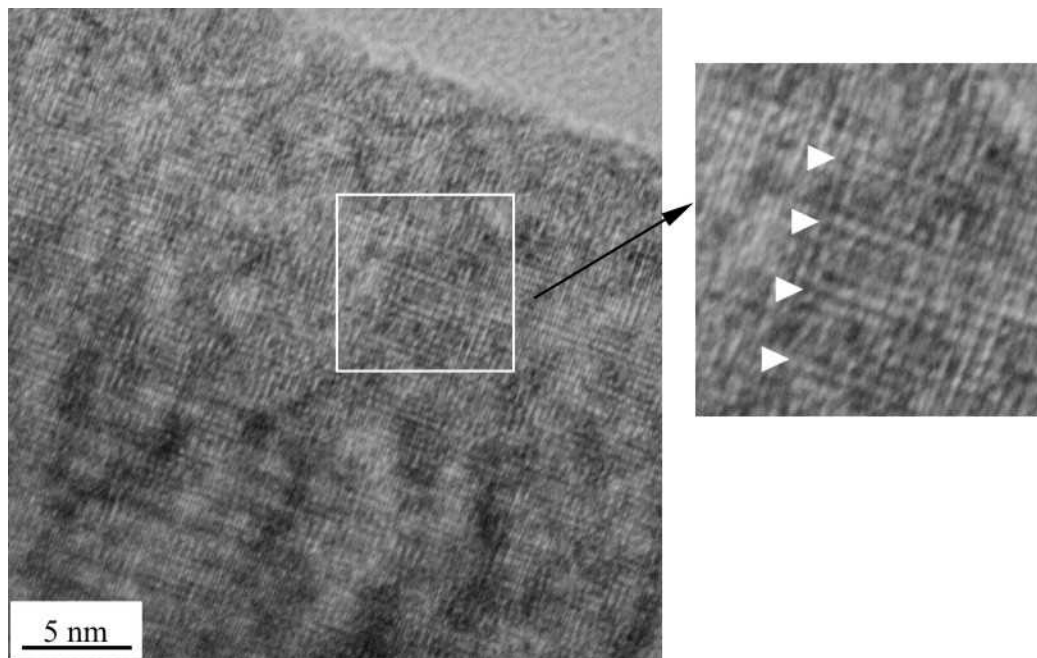


360 min

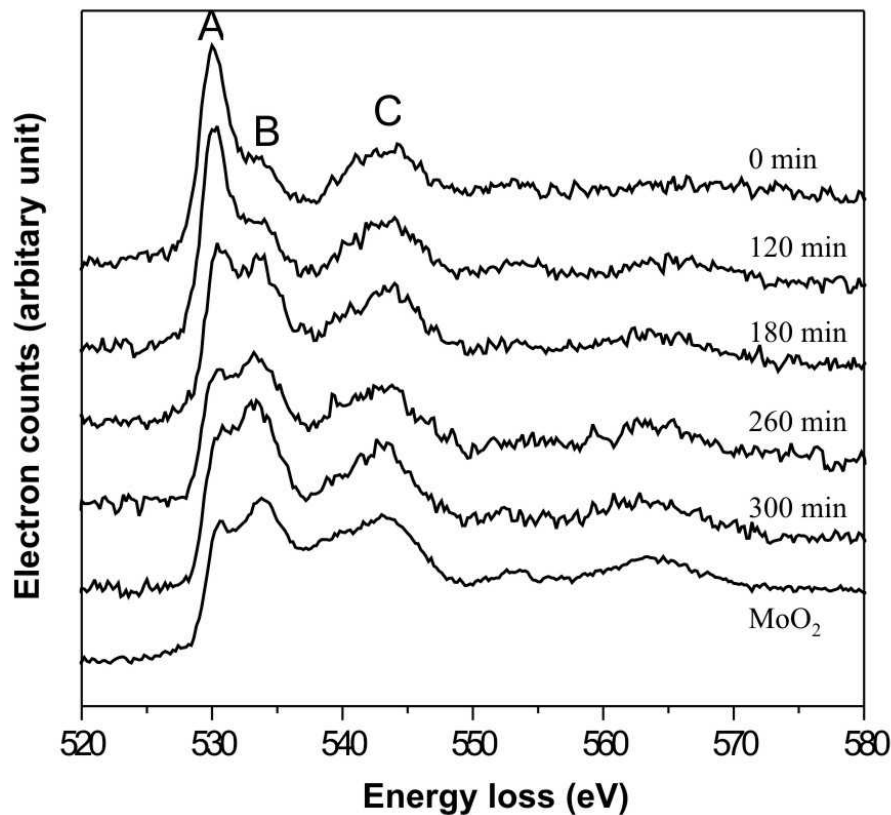
Frame 1 and 2: diffractions can be attributed to MoO_2 on $[-111]$ projection.

Frame 3: Diffractions can be attributed to MoO_2 on $[-122]$ projection.

HRTEM image showing contrast from CS structure, formed at the early stage of reduction.

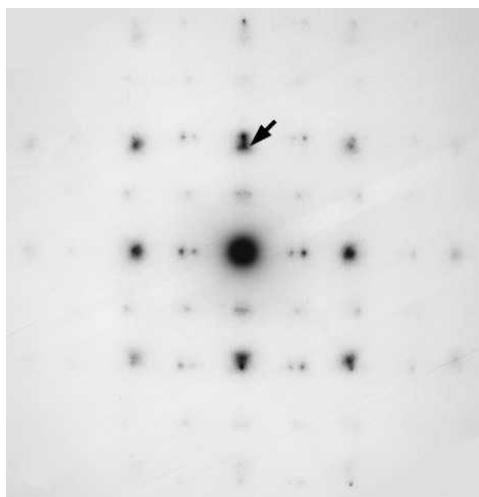


ELNES on O K-edge

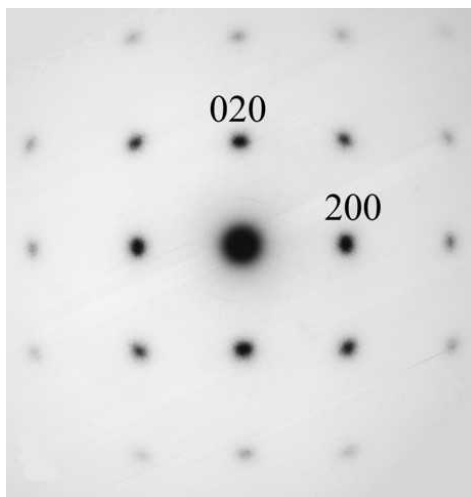


MoO₃: (MoO₆)⁶⁻ octahedral configuration

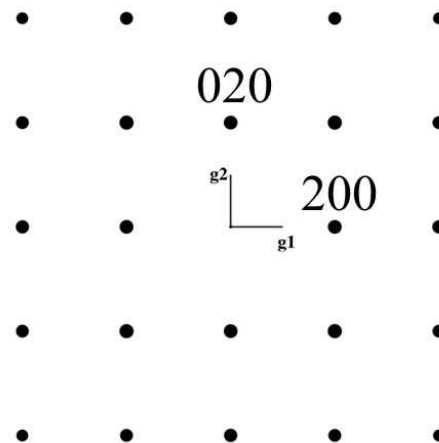
MoO₂: (MoO₆)⁸⁻ octahedral configuration
*t*_{2g} anti-bonding orbitals are partially filled by *two* electrons.



After irradiation of 10 min

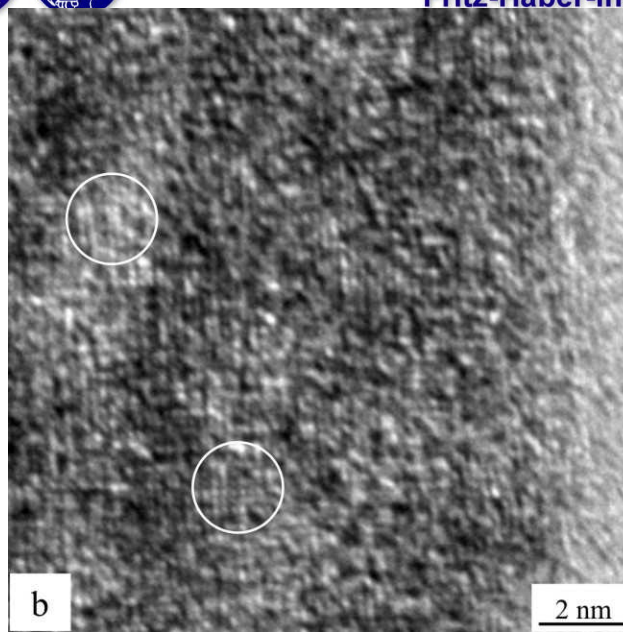
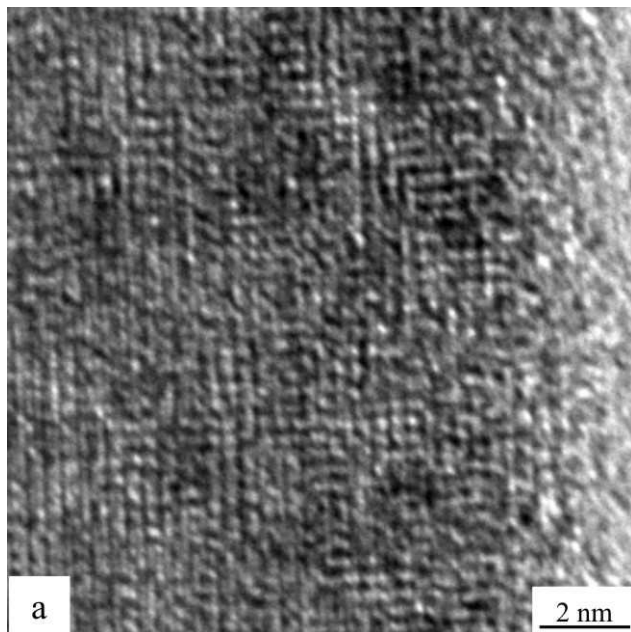


40 min

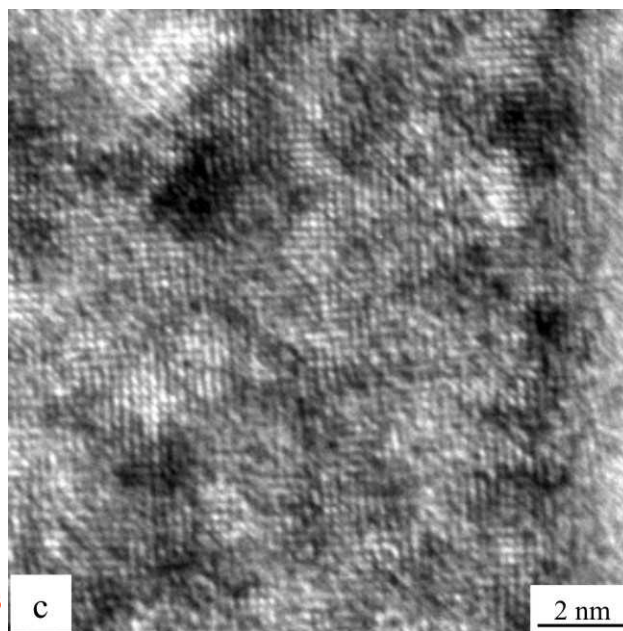


MoO ($a = b = c = 4.08 \text{ \AA}$) with *NaCl* structure? → Simulation

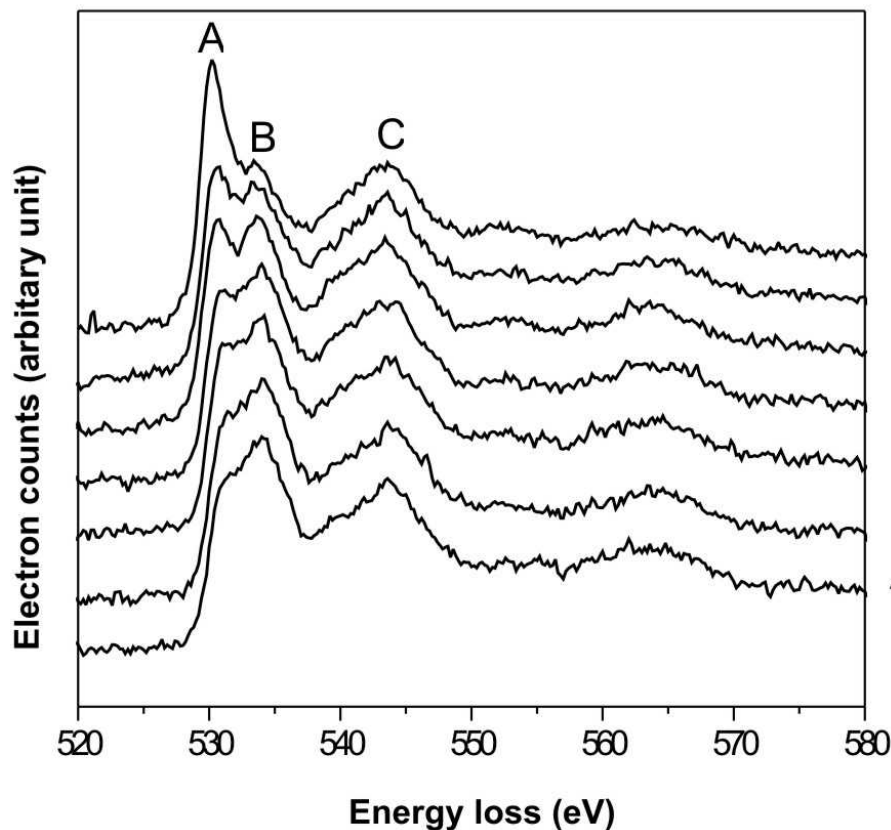
High electron current density



HRTEM images for evolution of Mo oxide under electron irradiation



ELNES on O *K*-edge



0 min MoO₃: (MoO₆)⁶⁻ octahedral configuration

40 min MoO: (MoO₆)¹⁰⁻ octahedral configuration
*t*_{2g} anti-bonding orbitals are partially filled by *four* electrons.

Summary

- Importance of model catalyst — simplifying complex system; facilitating analytic techniques; aware of the gap between the TEM environment and the “real” condition.
- Be sure that TEM observation on the *local* structure is representative to the whole catalyst.
- Distinguish electron induced effect from intrinsic features of catalyst



Literature

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